

Special Topics Presentation on Electron Sources – Part 1

Joe Grames, Jefferson Lab
October 15, 2012

(with many thanks for slides borrowed from
Carlos-Hernandez Garcia, Matt Poelker, Dave Dowell)

Electron emission in Nature

- Historically, electron emission musings go back to the Greek philosophers, who while rubbing pieces of amber (elektron in Greek) with fur noticed short flashes of light (sparks) jumping from the amber to the piece of silk.
- Effectively, a lighting strike is like a giant spark, generated when electrons 'jump' from the ground to the positively charged clouds.

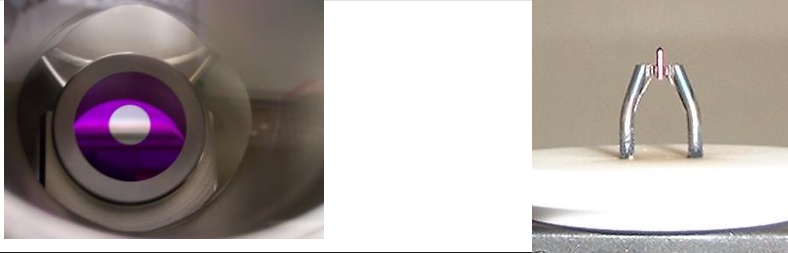


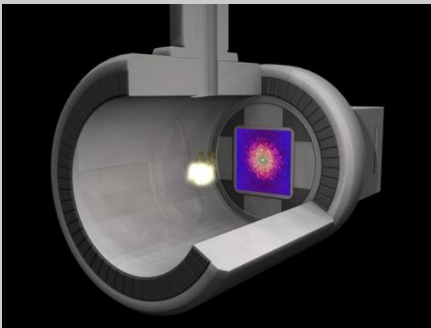
Electron emission *with a Purpose*

- Electron emission is the process in which electrons bound in a solid, are released and leave the surface of the solid.
- The process is statistical, as only those electrons with sufficient momentum component normal to the surface may overcome the surface barrier potential.

Why do accelerators need a particle source?

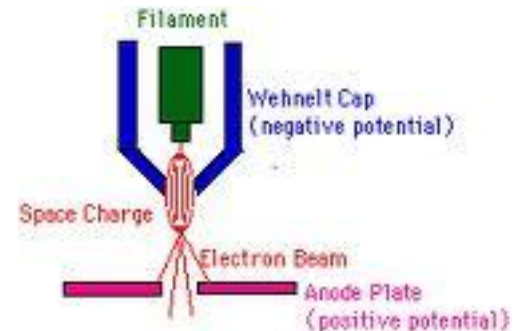
- Before being accelerated, the particles need to be generated first.
- Particles can be protons, ions, positrons, electrons, etcetera, depending on the specific accelerator application.
- The generation, or extraction mechanism, will depend on the desired type of particle and on the required beam characteristics.

Four essential ingredients are required to generate an electron beam

<p>The cathode, a material from which the electrons are extracted.</p>	
<p>A source of energy to excite electrons above the cathode's work function.</p>	
<p>An accelerating electric field to form a collimated beam (DC or oscillating) and overcome mutual Coulomb repulsion.</p>	
<p>A vacuum environment to prevent electron scattering by gas molecules and to preserve cathode chemistry</p>	

Electron microscopes

- In devices such as electron microscopes the electron beam is only a few μA of direct current (DC), emitted with very little spread (emittance) at $\sim 100 \text{ keV}$.
- Field emission from sharp (nm-size radius) metal needle cathodes is a typical choice, although many lower voltage devices (lower resolution) use thermionic cathodes.
- Required field at the tip for emission are in the order of Giga-Volts per meter.
- Tips are susceptible to contaminants (Carbon) and are easily damaged by over-current.



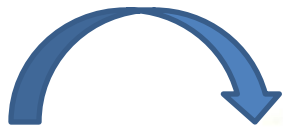
X-ray sources

Used to make x-ray light....

1880s

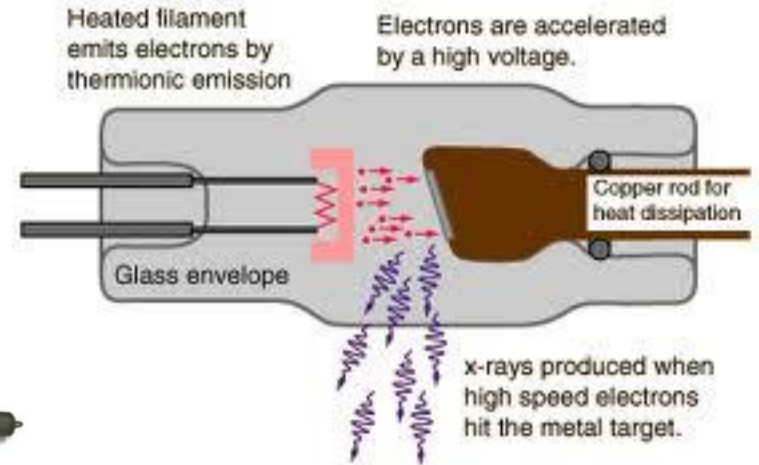


bias at high voltage

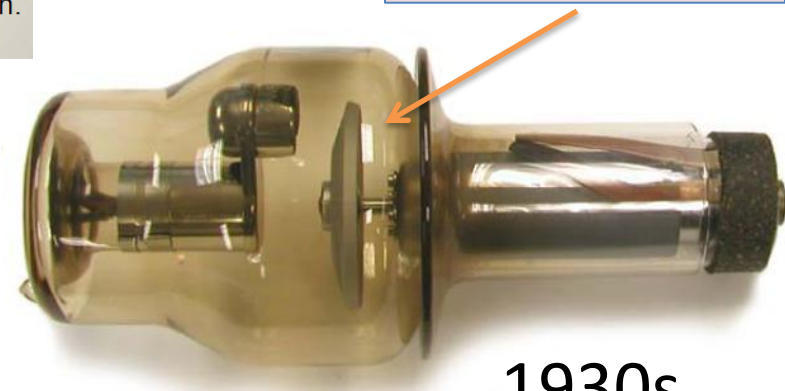


In 1913, William Coolidge invented an x-ray tube with high vacuum, a heated filament as electron source, and an x-ray producing anode. The tube, shown here, was produced in the 1920s by General Electric Corporation.

Photo: www.orau.org Oak Ridge Associated Universities



Rotating anode to distribute heat



1930s

X-rays are generated when a DC electron beam, typically a few mA, strikes a tungsten target at 60-200 keV. e-Beam quality is not a big concern

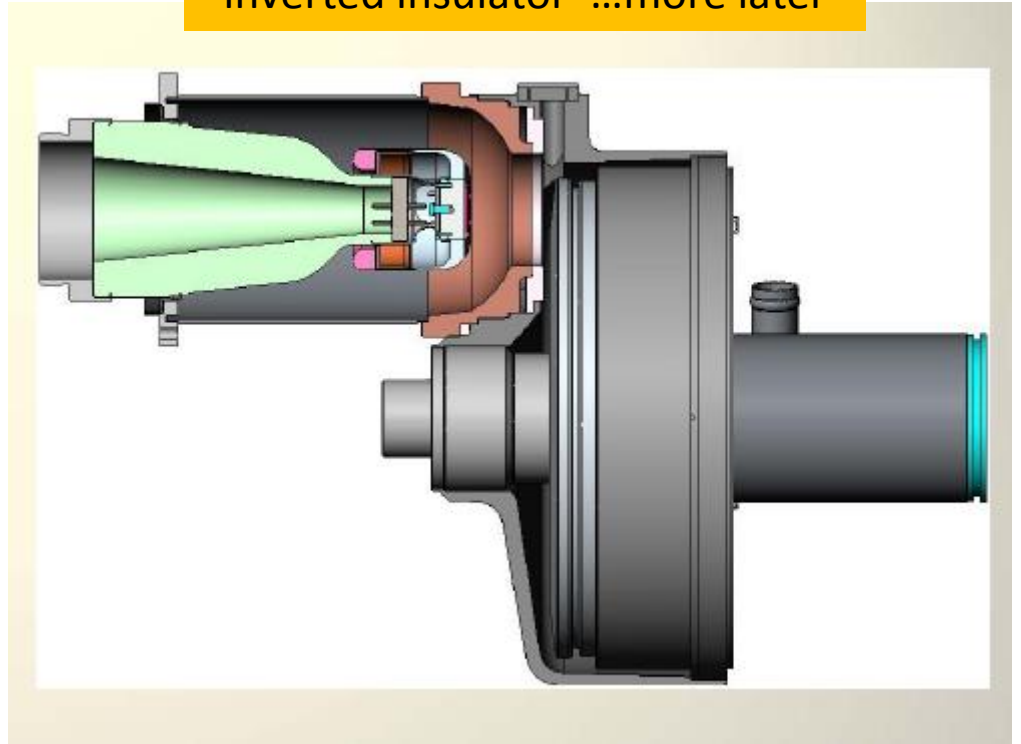
Modern X-Ray Sources



Higher Voltage....
More penetrating
x-ray beam

Higher e-beam current....
Higher x-ray flux

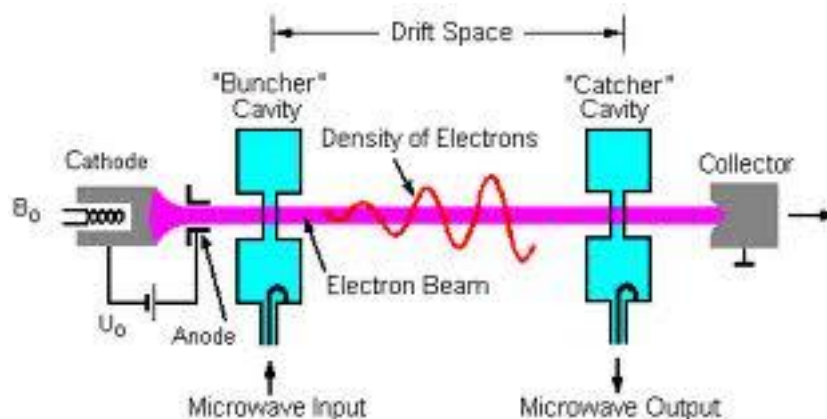
“inverted insulator” ...more later



Courtesy Varian

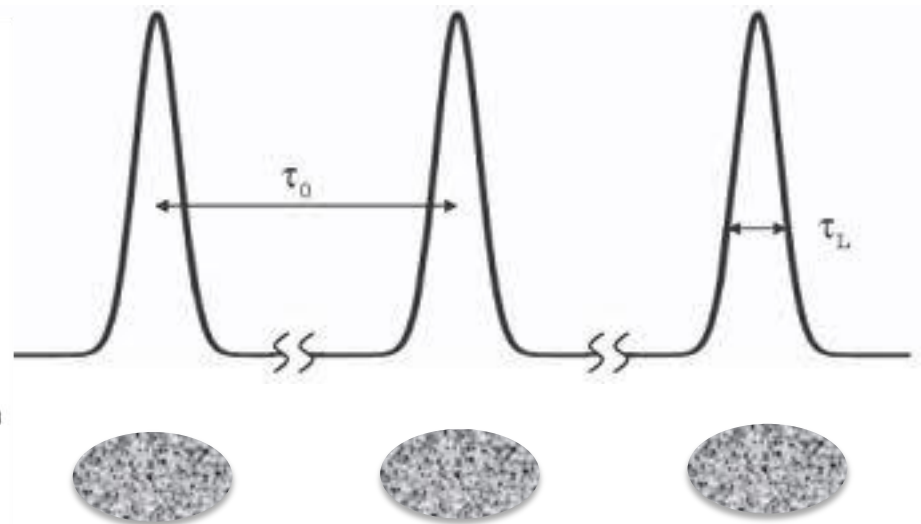
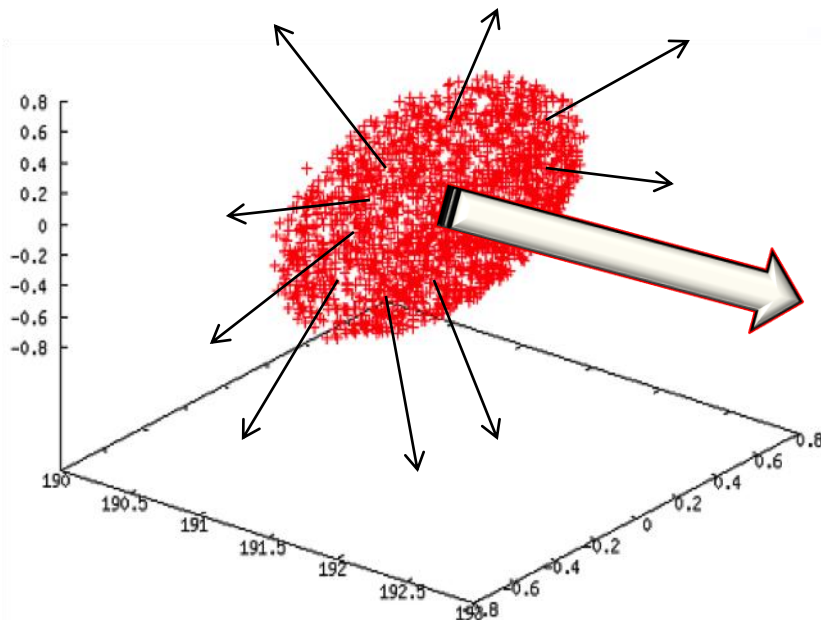
Klystrons—microwave generators

- Klystrons use a DC electron beam at a few mA to generate/amplify microwaves by velocity modulation.
- Klystrons use thermionic cathodes to generate the required electron beam.

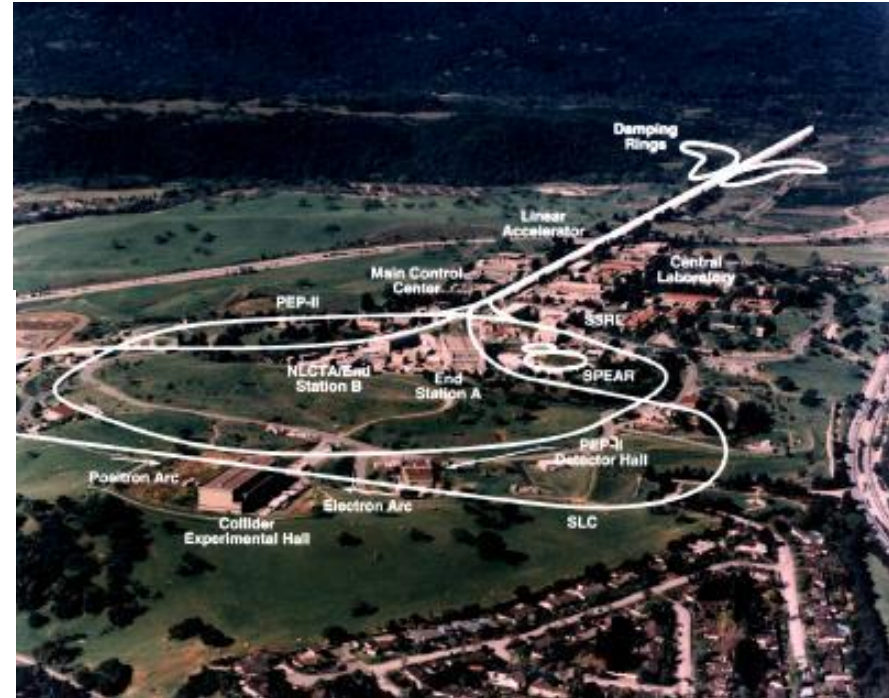
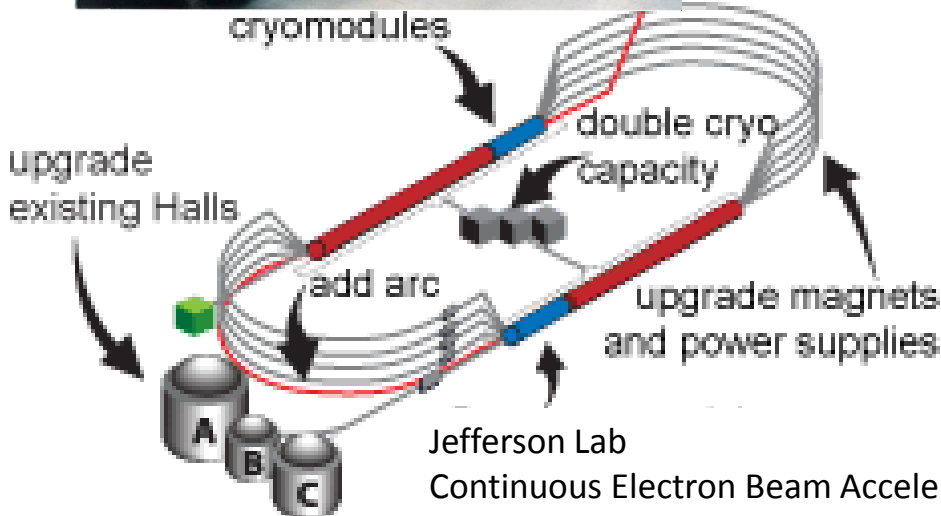


When electron beams need to be generated in pulses for accelerators

- The given examples so far use DC electron beams
- Most electron accelerators require the beam to be comprised of a train of electron pulses. In each pulse, there is a certain number of electrons with collective charge in the range of a few pC to a few nC. Each group of electrons is called an electron bunch.
- The rate at which the electron bunches are generated is called the pulse repetition rate.



As a point-like probe in the form of Polarized electrons for High Energy and Nuclear Physics research

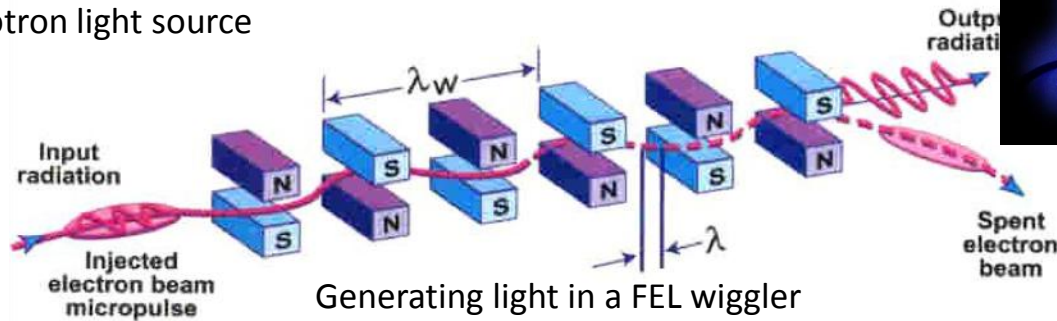
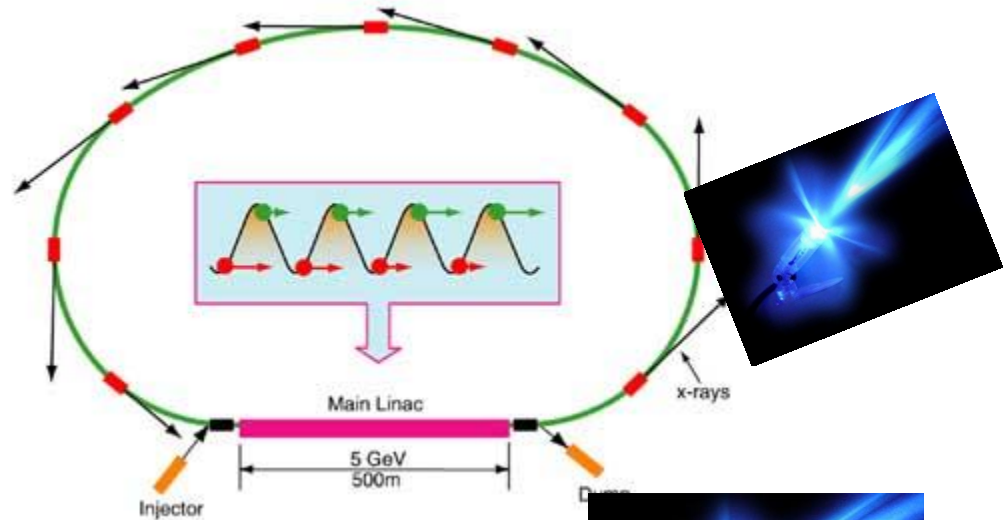


Stanford Linear Accelerator

As a source in the form of Un-polarized electrons for producing IR to X-ray photons in machines like Storage Rings, Synchrotrons and Free Electron Lasers

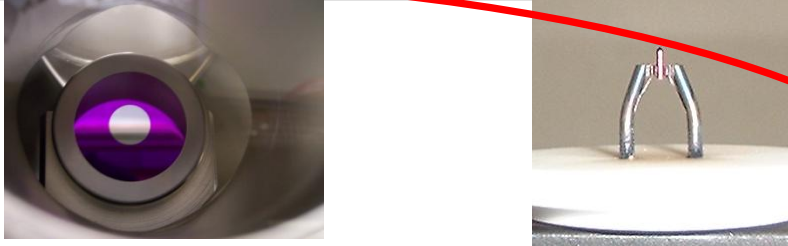


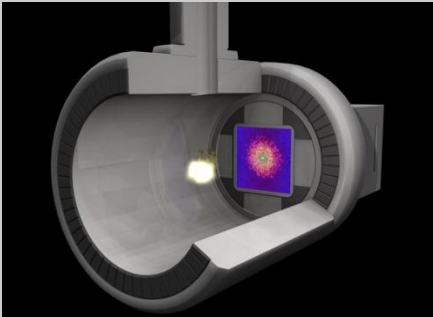


Argonne National Lab
Synchrotron light source



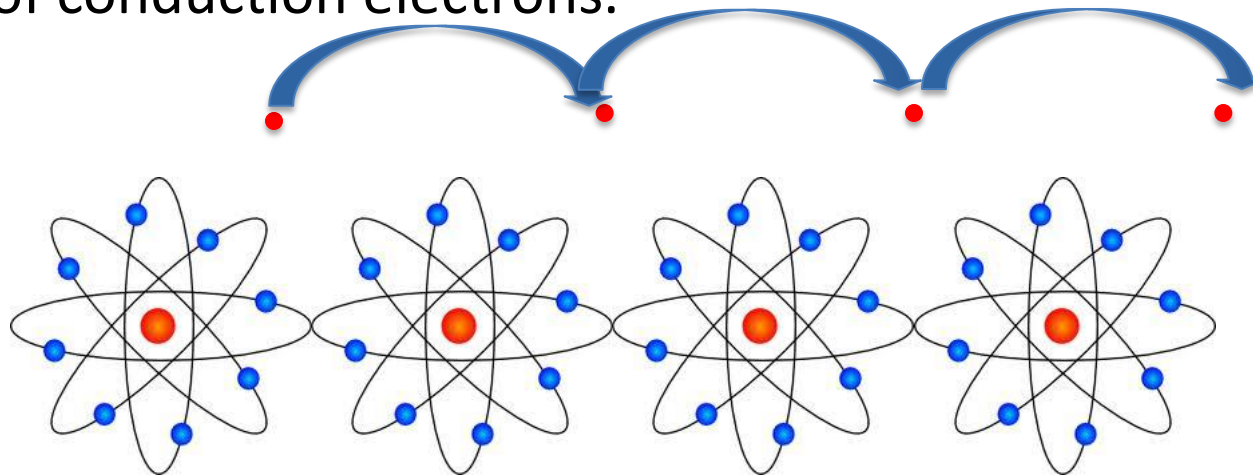
Generating light in a FEL wiggler

Four essential ingredients are required to generate an electron beam

<p>The cathode, a material from which the electrons are extracted.</p>	
<p>A source of energy to excite electrons above the cathode's work function.</p>	
<p>An accelerating electric field to form a collimated beam (DC or oscillating) and overcome mutual Coulomb repulsion.</p>	
<p>A vacuum environment to prevent electron scattering by gas molecules and to preserve cathode chemistry</p>	

Electron emission from metals

- In metals, electrons in the outer atom shells are not bound to a particular atom, rather they are in continuous motion “hopping” from atom to atom, but still bound to the metal surface.
- In some sense the electron can be considered as a “Free Electron Gas” in which the atomic cores are immersed in a sea of conduction electrons.



Why metals reflect light so well?

The free electron Fermi gas

- The Fermi energy is defined as the energy of the topmost filled level in the ground state of the N electron system, at absolute zero.

$$E_F = \frac{\hbar^2}{2m} (3\pi^2 N_e)^{2/3}$$

- What happens when the temperature is increased? The Fermi-Dirac distribution gives the probability that an electron state of energy E will be occupied at thermal equilibrium with temperature T.

$$f(E, T) = \frac{1}{1 + \exp\left[\frac{(E - E_F)}{k_B T}\right]}$$

The free electron Fermi gas

- The density of states describes the distribution of possible states in the solid per unit volume:

$$\rho(E) = \frac{1}{2\pi^2} \left(\frac{2m}{\hbar^2} \right)^{3/2} E^{1/2}$$

- The number of electrons per unit volume, which is the baseline for calculating electron emission.

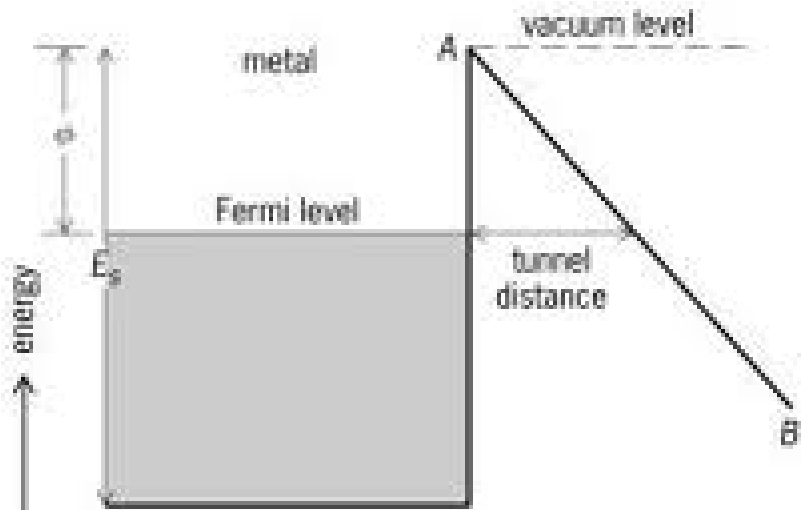
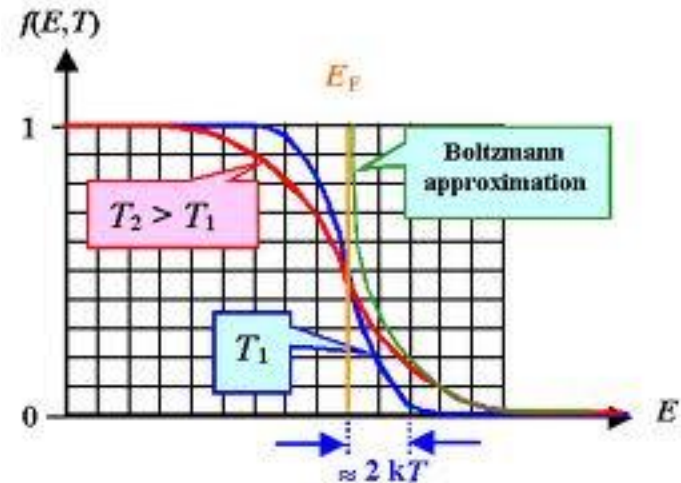
$$N_e = \int_0^{\infty} \rho(E) f(E, T) dE$$

The free electron Fermi gas

As the temperature is increased, more and more electrons gain energies higher than the Fermi energy and higher probability to escape into the vacuum level.

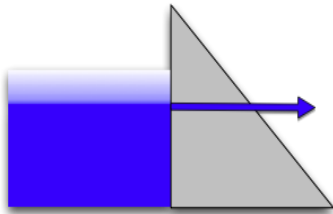
The vacuum level is defined as the distance at which an electron is sufficiently far from the metal surface that its image charge is negligible (more than 100 Angstroms)

The work function Φ is defined as the difference in potential energy of an electron between the vacuum level and the Fermi level.



The canonical emission equations

(slide courtesy of Dr. K. Jensen, Naval Research Laboratory)

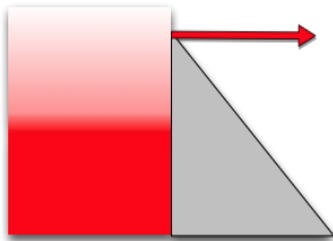


- **Field Emission**

Fowler nordheim

E.L. Murphy, and R.H. Good,
Physical Review 102, 1464 (1956).

$$J_{FN}(F) = A_{FN} F^2 \exp\left(-\frac{B\Phi^{3/2}}{F}\right)$$

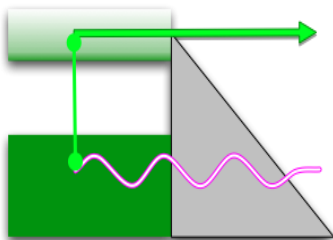


- **Thermal emission**

Richardson-Laue-Dushman

C. Herring, and M. Nichols,
Reviews of Modern Physics 21, 185
(1949).

$$J_{RLD}(T) = A_{RLD} T^2 \exp\left(-\frac{\Phi}{k_B T}\right)$$



- **Photoemission**

Fowler-Dubridge

L.A. DuBridge
Physical Review 43, 0727 (1933).

$$J_{MFD}(\lambda) = \frac{q}{\hbar\omega} (1-R) F_{\lambda}(\omega) \{\hbar\omega - \Phi\}^2 I_{\lambda}$$

Listed chronologically

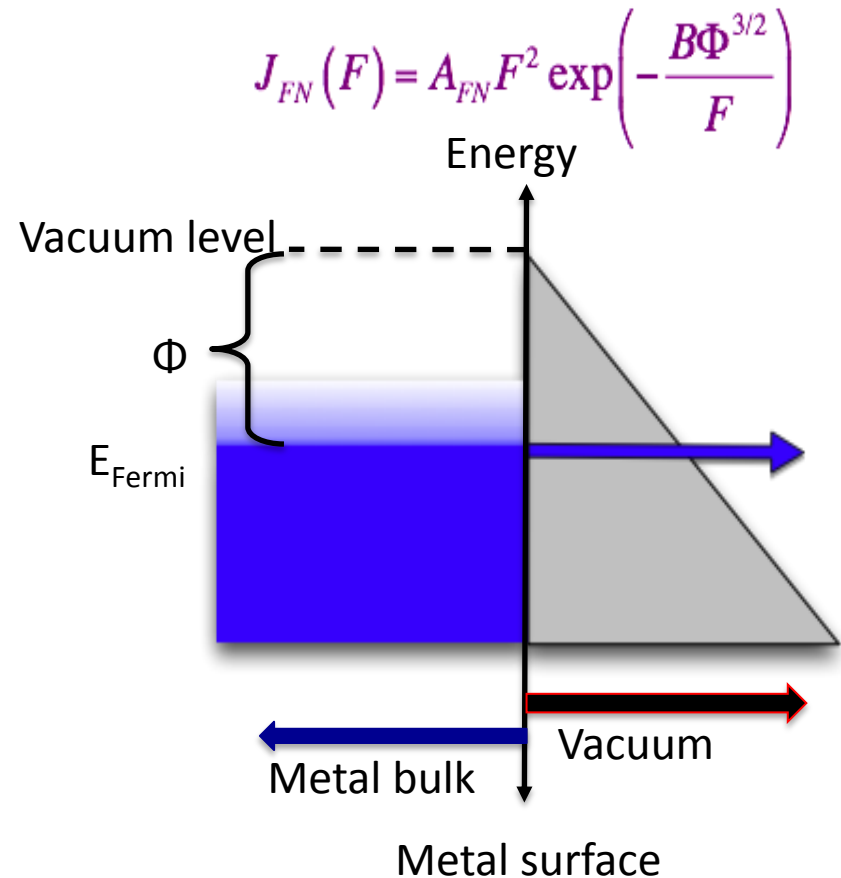
Field Emission

High field and low temperature

Fowler-Nordheim

E.L. Murphy, and R.H. Good, Physical Review 102, 1464 (1956).

- In Field Emission, the electrostatic field (F) at the metal surface is so high it thins the potential barrier.
- Electrons with energies below the Fermi level with momentum component perpendicular to the metal surface have then a finite probability to tunnel through the thinned potential barrier, with current density $J(F)$.
- Field Emission occurs when the field is >1 GV/m, typically in sub-micron size metallic tips.



Φ = Work function, $\sim 4-5$ eV

Thermal Emission

High temperature and low field

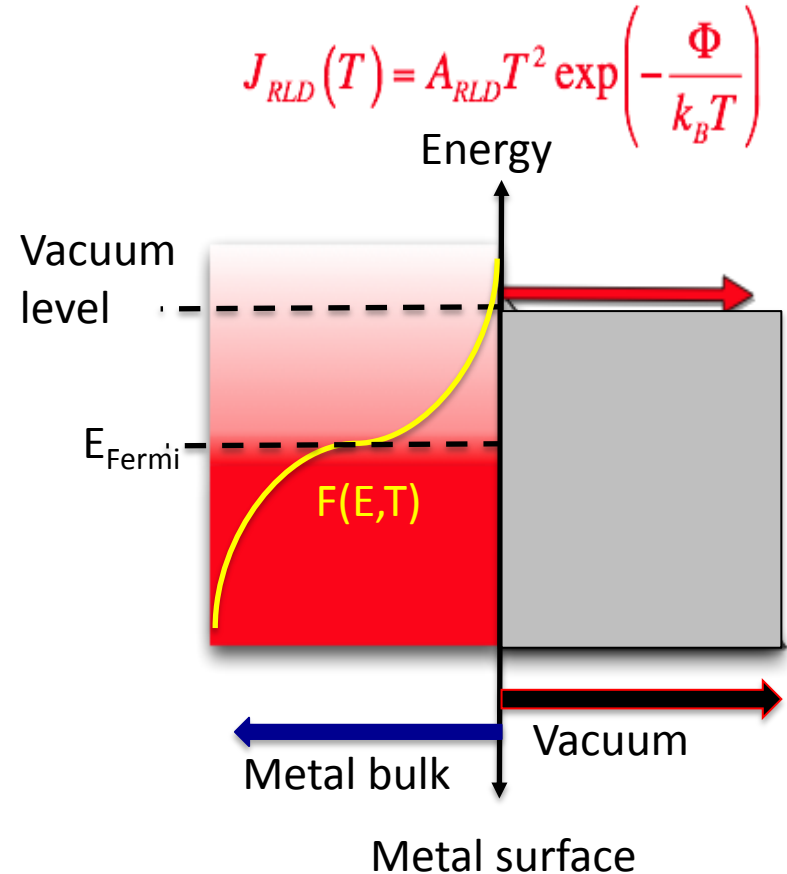
Richardson-Laue-Dushman

C. Herring, and M. Nichols, Reviews of Modern Physics 21, 185 (1949).

- In thermal emission, electrons gain sufficient thermal energy to overcome the vacuum level. Those electrons with momentum component perpendicular to the metal surface have a finite probability of being emitted with current density $J(T)$.
- In thermionic emission, application of an external field lowers the metal work function. This is known as the Schottky enhancement factor.

$$\phi_{\text{effective}} = \phi_{\text{metal}} - \phi_{\text{Schottky}}$$

$$\phi_{\text{Schottky}} = e \sqrt{\frac{eE_{\text{applied}}}{4\pi\epsilon_0}}$$



Φ = Work function, ~4-5 eV

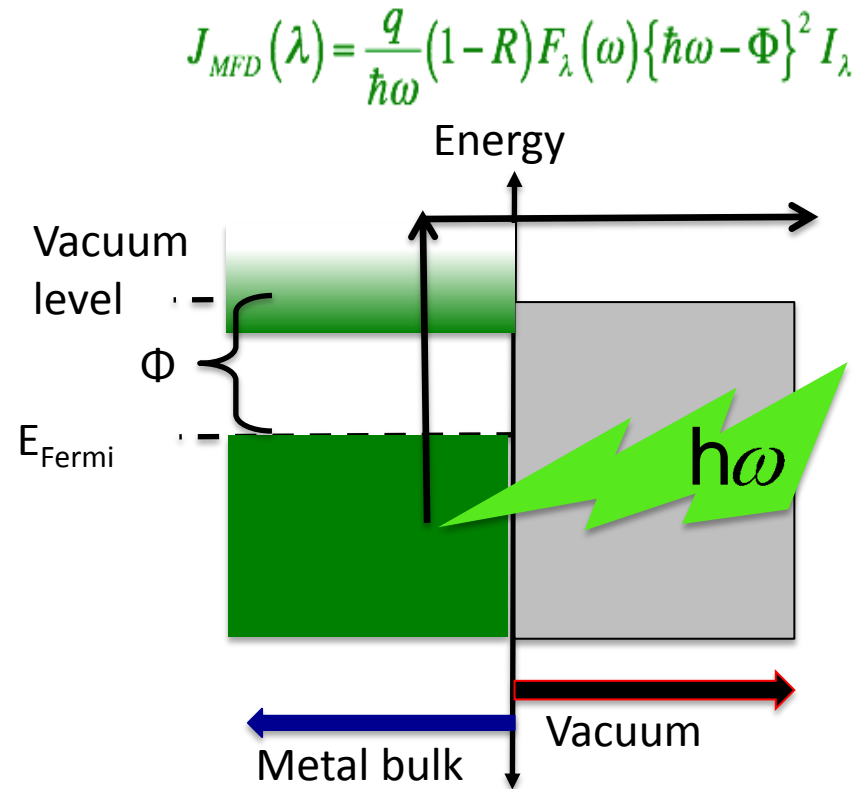
Photoemission

Low temperature and low field

Fowler-Dubridge

L.A. DuBridge, Physical Review 43, 0727 (1933).

- Photoemission occurs in metals when the incident photon energy exceeds the work function.
- The current density J depends on the photon flux, absorption and wavelength, as well as scattering and emission probability mechanisms.
- Photoemission is a three step process



Metal surface

Φ = Work function, ~4-5 eV

$\hbar\omega$ Photon energy in eV

Photoemission from intrinsic semiconductors

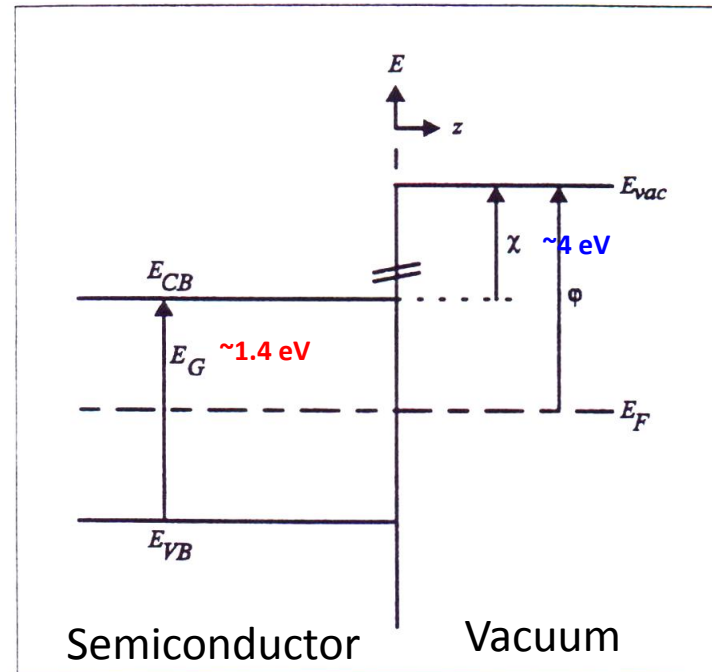
E_{VB} = Valence band

E_{CB} = Conduction band

E_{vac} = Vacuum level

E_F = Fermi level

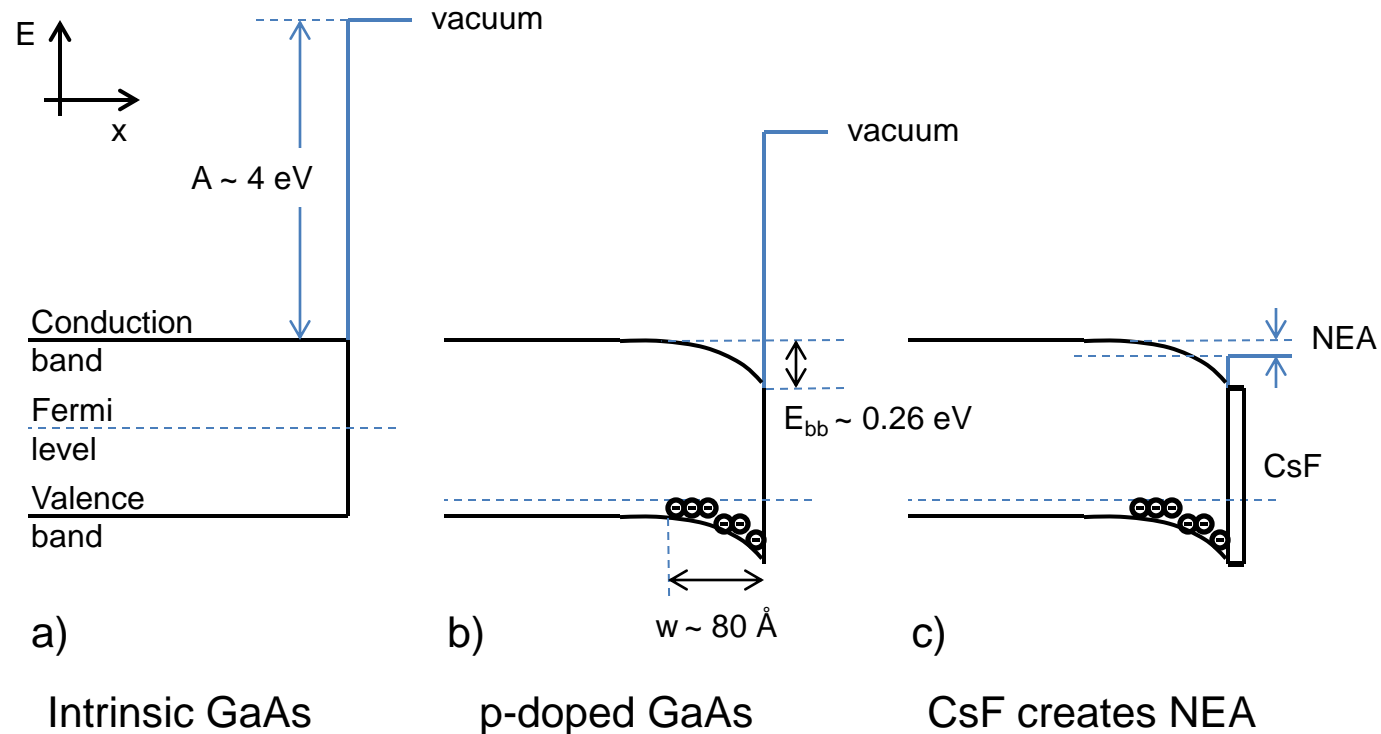
χ = Electron affinity, typically around 4 eV



$$\chi = E_{vac} - E_{CB} \text{ Electron affinity } \sim 4 \text{ eV for GaAs}$$

$$\phi = E_{vac} - E_F \text{ Work function}$$

Reducing the Work Function



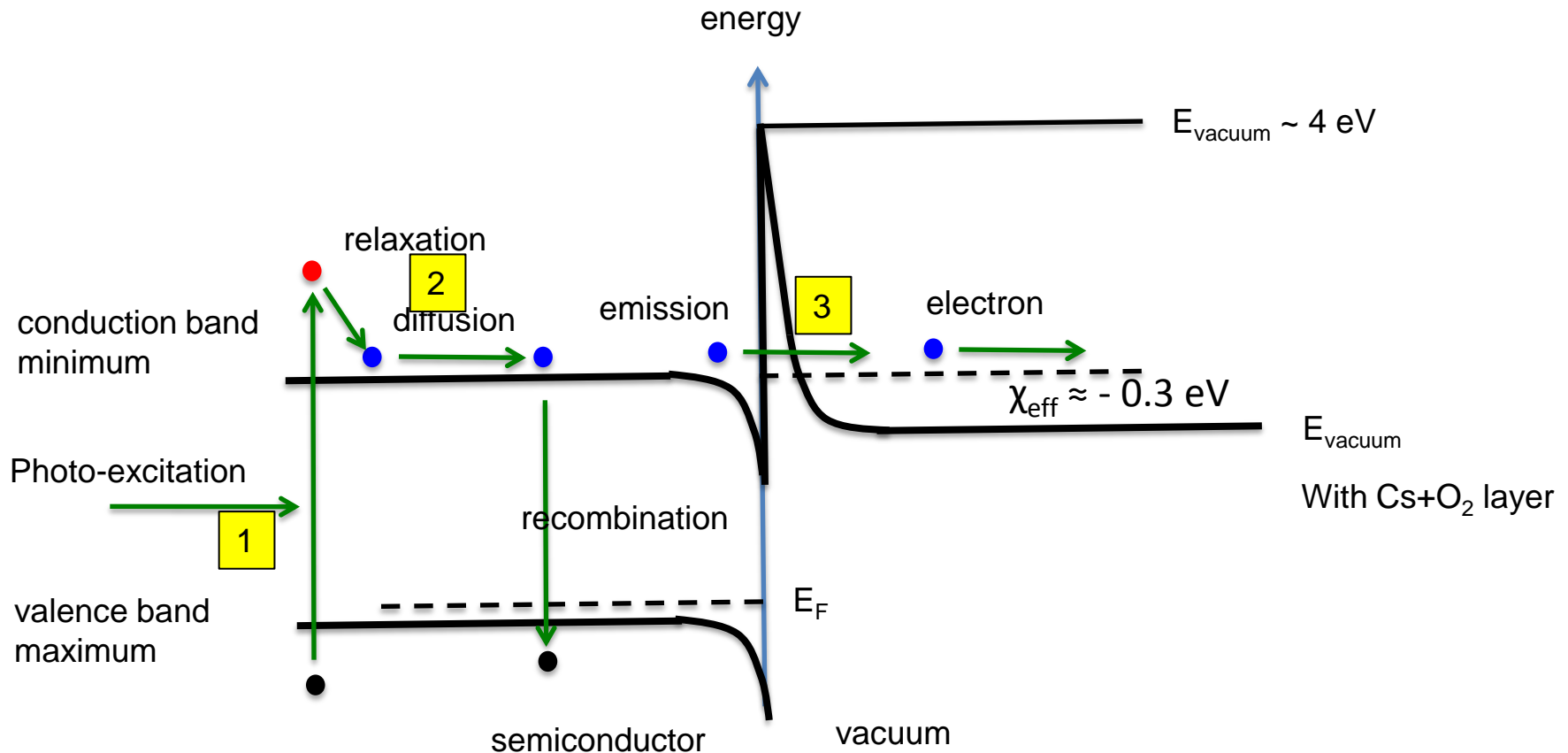
Doping adds additional energy states in the gap, adjusting the Fermi level in the bulk, pulling E_c , E_v and vacuum level at surface (forming so-called band bending region)...

The three components of Photoemission process (Spicer model, 1958)

(slide courtesy of Dr. K. Jensen, Naval Research Laboratory)

1. **Absorption** of light in bulk material and photo-excitation of electrons.
 - Light intensity and wavelength (photon energy)
 - Material reflectivity
 - Light penetration depth
2. **Transport** of photo-excited electrons to the surface
 - Electron energy
 - Scattering rates (relaxation times)
3. **Emission** probability
 - For metals: Chemical potential and work function
 - For semiconductors: barrier height and band gap
 - Electron affinity measured from the conduction band minimum

Three step photoemission in NEA-GaAs (Spicer model, 1958)*

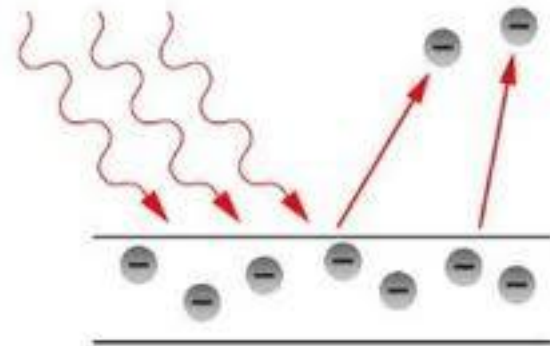
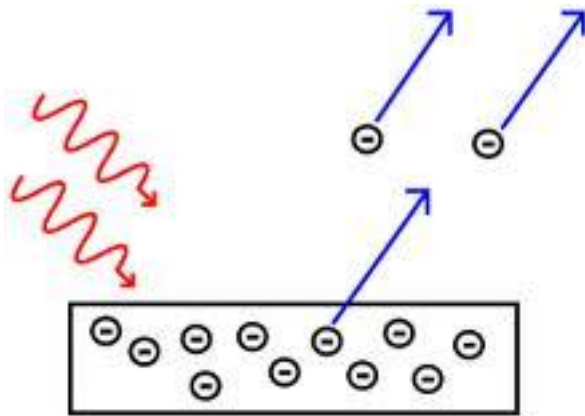


* Still not fully understood

Quantum Efficiency

- Generically the quantum efficiency is defined as the ratio of emitted electrons to incident photons.

$$QE = \frac{N_{electrons}}{N_{photons}}$$



Quantum Efficiency

(slide courtesy of Dr. K. Jensen, Naval Research Laboratory)

- In Metals, QE is dominated by the energy difference between the incident photon and the work function.

$$QE = (1 - R(\omega)) F_{\omega}(\delta, \tau) [P(\hbar\omega) \propto (\hbar\omega - \phi)^2]$$

Modified Fowler-Dubridge Model for Metals

- In Semiconductors, QE is dominated by the energy difference between the incident photon and the band gap.

$$QE \approx \frac{B}{1 + g [\hbar\omega - (E_g + E_a)]^s}$$

Spicer's three Step Model for semiconductors

E_g = Energy gap between bottom of conduction band and top of valence band

E_a = Energy gap between bottom of conduction band and vacuum level. *This is the effective electron affinity*

B = escape X transport term

g = absorption factor

s = semi-empirical, argued 3/2.

In practical terms, this is the QE equation

$$QE(\%) = \frac{124}{\lambda_{laser}} \cdot \frac{I}{P_{laser}}$$

λ = laser wavelength (nm)

P = (mW)

I = Photo-current (μ A)

124 = Constant. Hint! Derive this constant.

QE is low in metals (<0.003%) because of electron-electron scattering in the conduction band

QE in semiconductors is typically 1-10% because scattering is between electrons and phonons, i.e. electrons thermalize with the lattice

Practicalities

- The choice of a particular emission mechanism and associated cathode is mainly driven by the electron beam requirements, specified by the device/accelerator, and by the technical constraints of the electron source as a whole system.
- There is no single source that can meet the requirements for all applications.
- Let's explore an electron source of a particle accelerator.

Jefferson Lab

Thomas Jefferson National Accelerator Facility

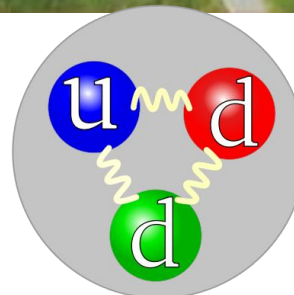
Exploring the Nature of Matter



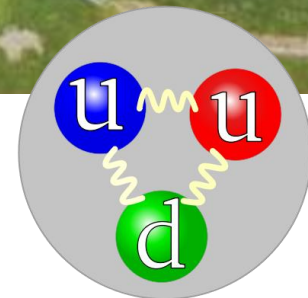
Jefferson Lab accelerator site



Electron



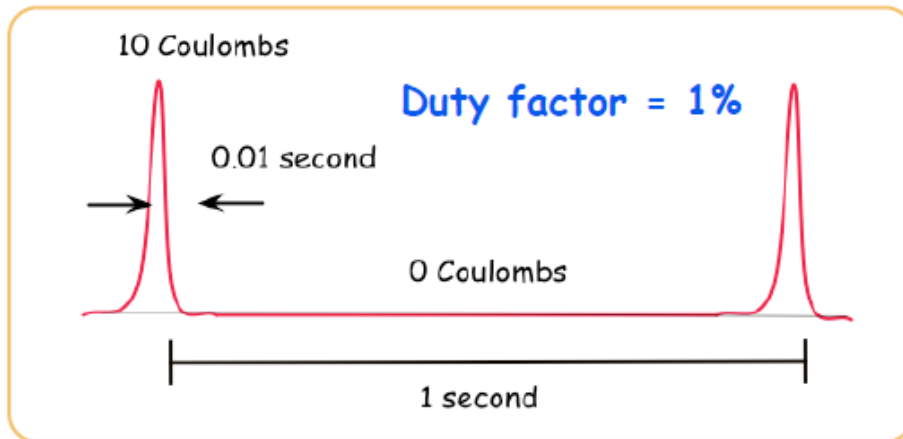
Neutron



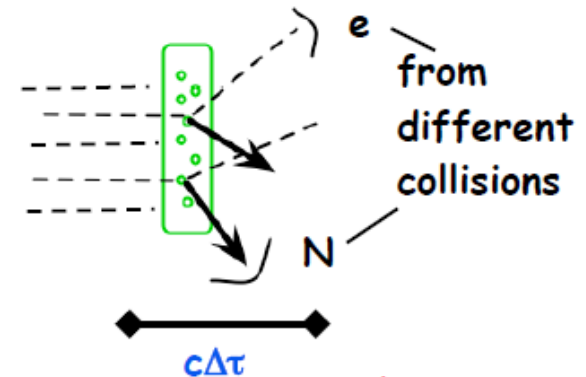
Proton

The “C” in CEBAF

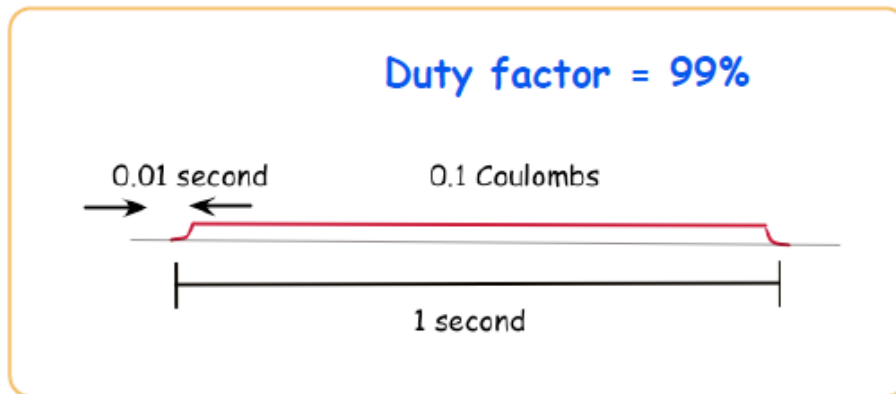
- ★ Pulsed beams used prior to 1980 (100 mA)



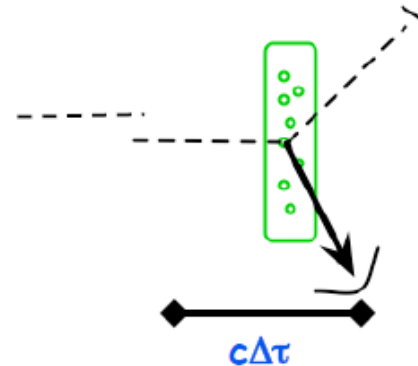
too many electrons in the target over the time interval $\Delta\tau$
lots of random coincidences



- ★ Advantages of a continuous beam with the same average current

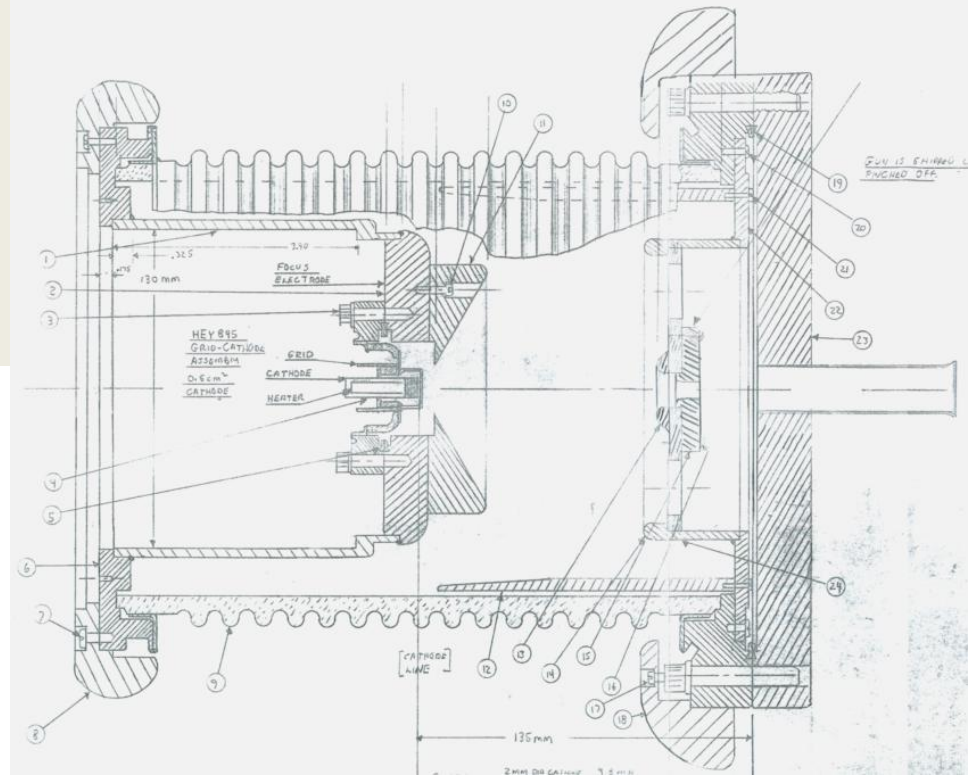


few electrons in the target --
few random coincidences



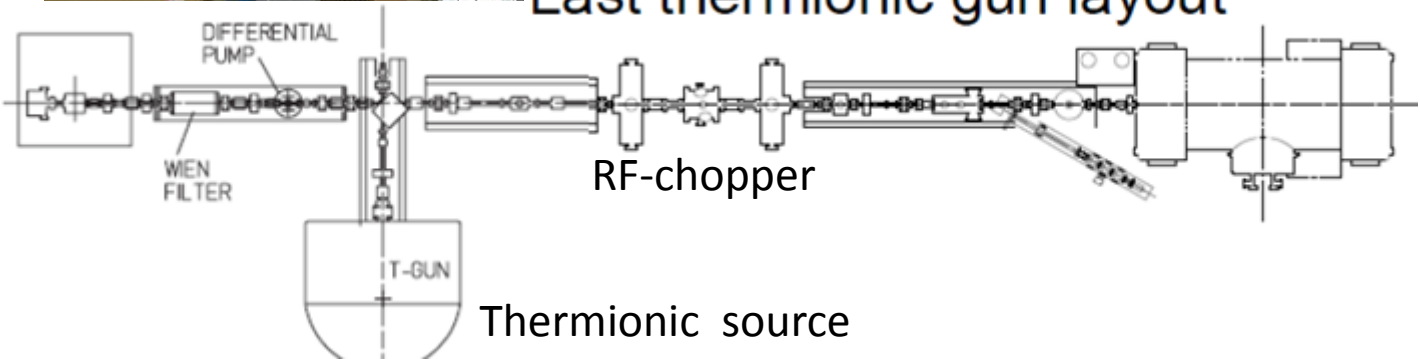
CEBAF's First Electron Source

- Make beam by running current through the filament biased at 100kV
- Use “grid” to turn beam ON/OFF, i.e., create machine-safe macropulses
- Apertures to improve emittance
- Use RF “chopper” to create RF structure



Last thermionic gun layout

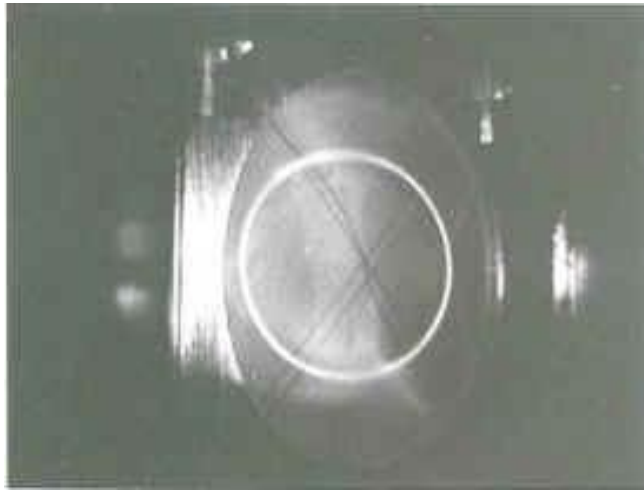
Polarized GaAs
photosource



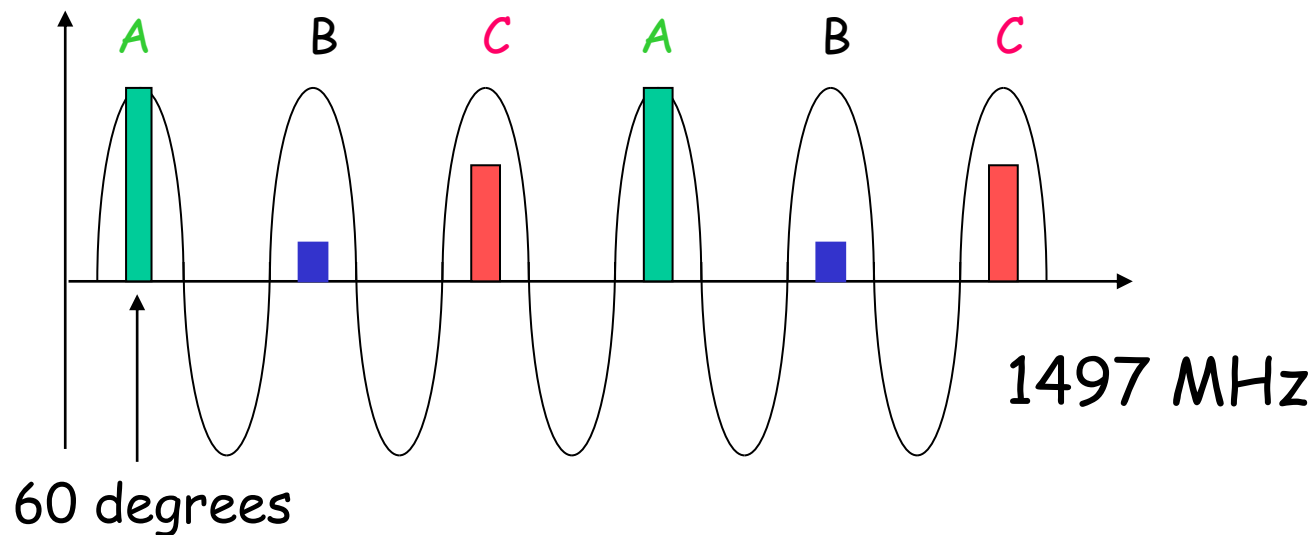
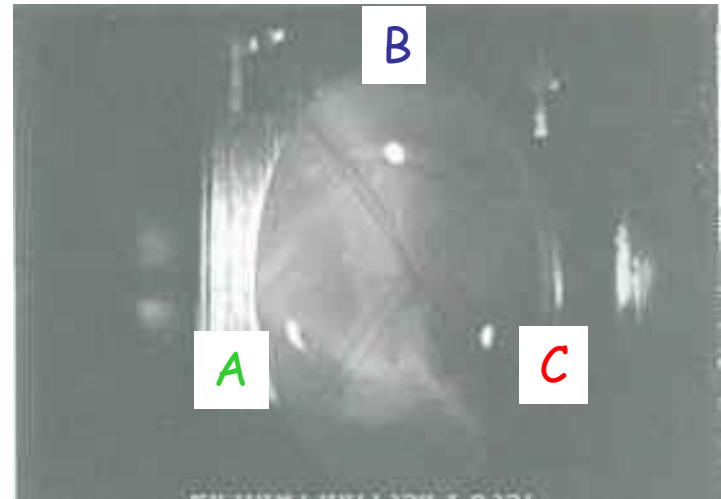
Thermionic source

Photo Finish, but at 2 billionths of a second !!!

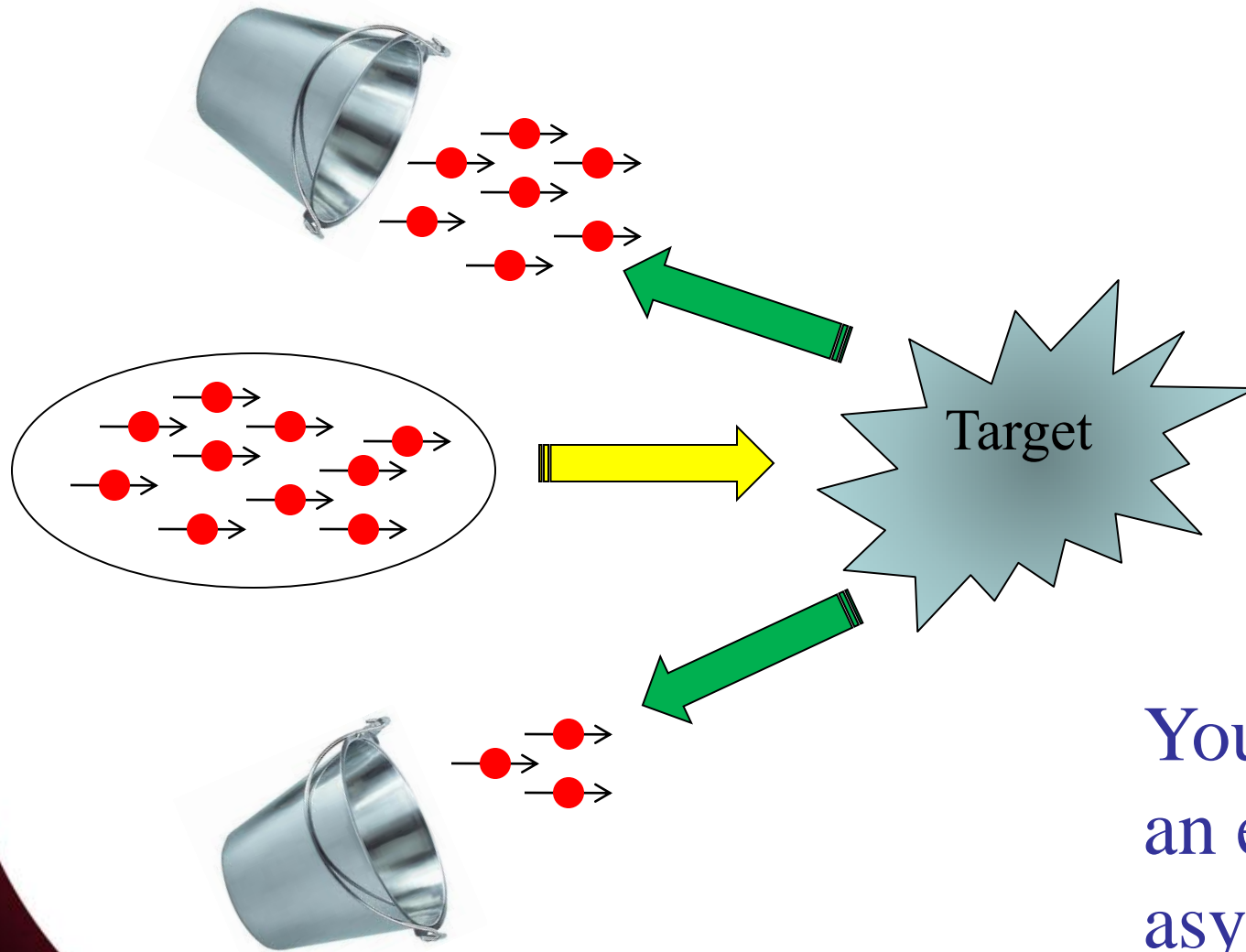
DC beam, not so useful
for RF acceleration



Beam of Bunches!



What about the probing with spin ?



You measure
an experimental
asymmetry

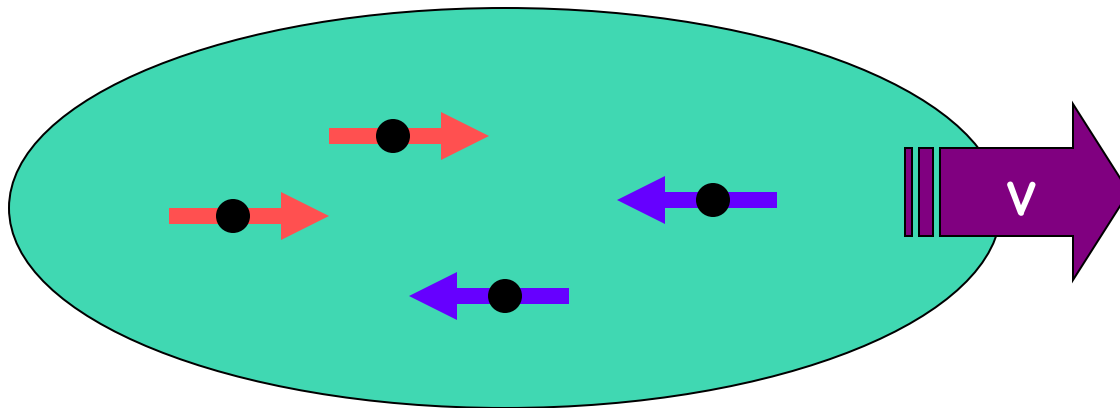
Electron Bunch Spin & Polarization

People with very different opinions

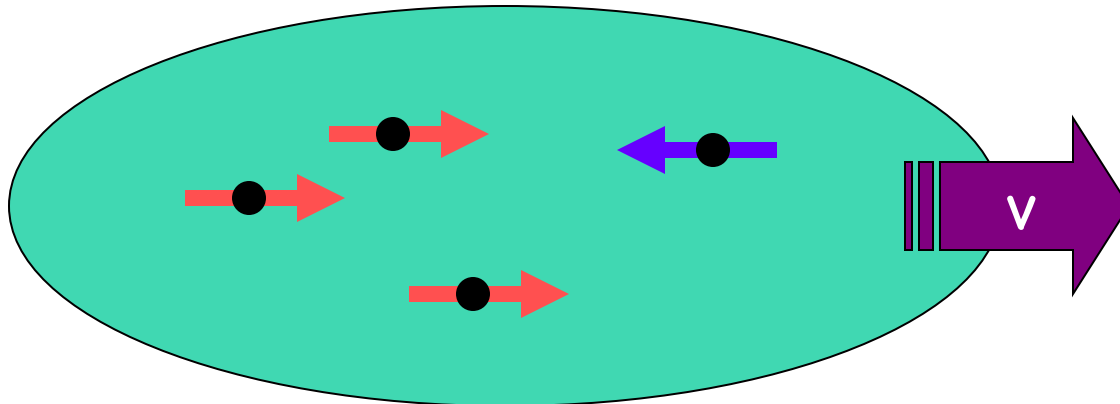
Light: a preference for the electric field vector to be oriented a certain way

Electrons: a preference for electrons to spin in one direction

$$P_e = \frac{N_{\uparrow} - N_{\downarrow}}{N_{\uparrow} + N_{\downarrow}}$$



0% Polarization



50% Polarization

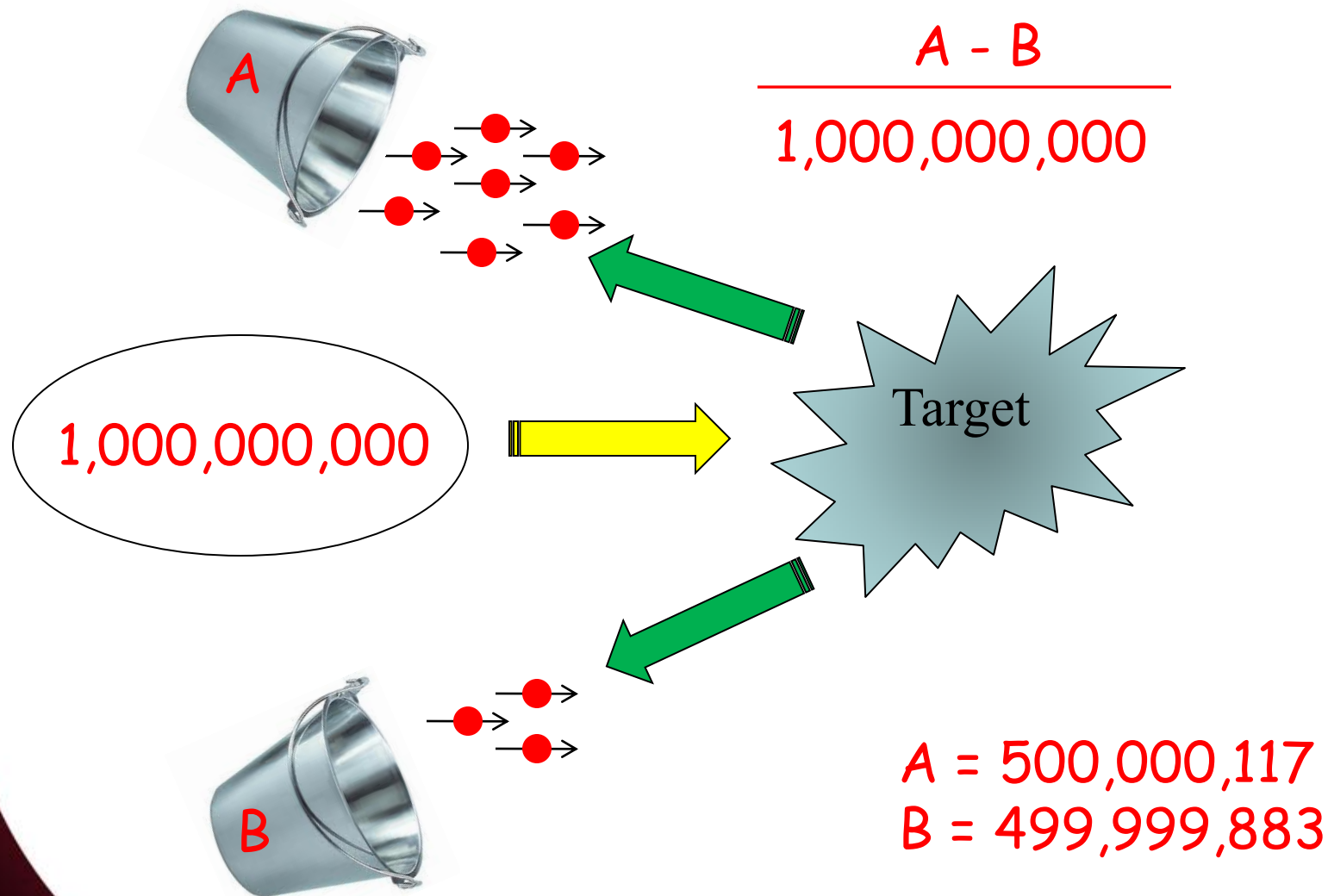


Parity Violation Experiments at CEBAF

Experiment	Energy (GeV)	I (μ A)	Target	A_{pv} (ppb)	Maximum Charge Asym (ppb)	Maximum Position Diff (nm)	Maximum Angle Diff (nrad)	Maximum Size Diff ($\delta\sigma/\sigma$)
HAPPEx-II (Achieved)	3.0	55	^1H (20 cm)	1400	400	1	0.2	Was not specified
HAPPEx-III (Achieved)	3.484	100	^1H (25 cm)	16900	200 \pm 100	3 \pm 3	0.5 \pm 0.1	10 ⁻³
PREx	1.063	70	^{208}Pb (0.5 mm)	500	100 \pm 10	2 \pm 1	0.3 \pm 0.1	10 ⁻⁴
QWeak	1.162	180	^1H (35 cm)	234	100 \pm 10	2 \pm 1	30 \pm 3	10 ⁻⁴
Møller	11.0	75	^1H (150 cm)	35.6	10 \pm 10	0.5 \pm 0.5	0.05 \pm 0.05	10 ⁻⁴

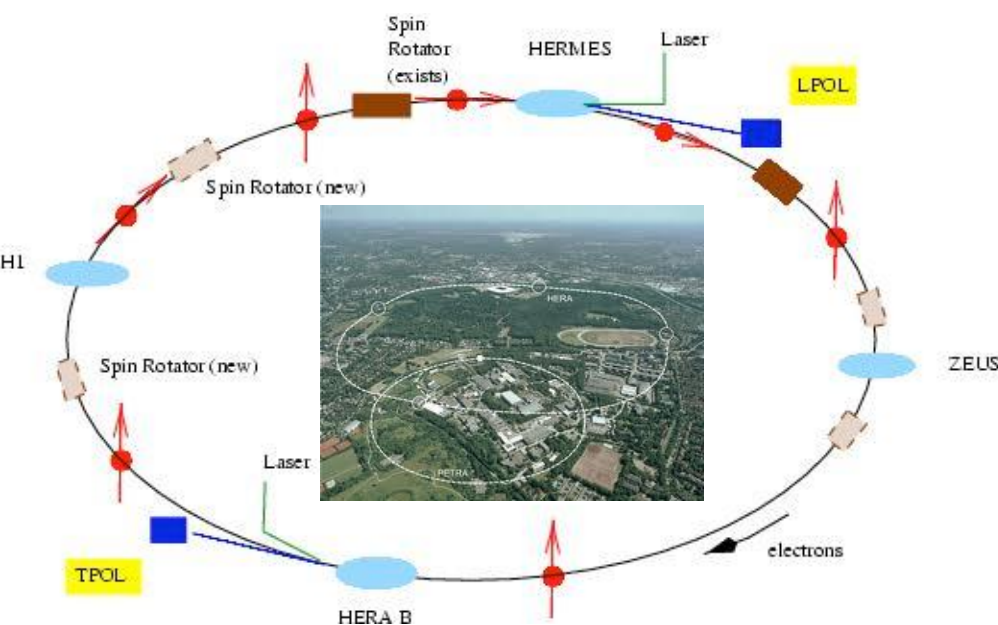
PV experiments motivate polarized e-source R&D

What does “234 ppb” even mean?



Self-Polarization: Sokolov-Ternov Effect

- Electrons (positrons) self-polarize in storage rings due to spin-flip synchrotron radiation: one spin state dominates the other
- First observed @ VEPP-2 Ring at Budker Institute, Novosibirsk, 1971
- Requires spin rotation (Siberian Snake) to create longitudinal polarization at target & depolarizing resonances must be avoided
- Process is slow, need storage lifetime to be longer than self-polarization time & happy to end up with ~70% polarization



$$P_{ST} = \frac{\omega_{\uparrow\downarrow} - \omega_{\downarrow\uparrow}}{\omega_{\uparrow\downarrow} + \omega_{\downarrow\uparrow}} = \frac{8}{5\sqrt{3}} \approx 92.4\%$$

$$P_Y(t) = -P_{ST} (1 - e^{-t/\tau_{ST}})$$

$$\tau_{ST} = \frac{1}{\omega_{\uparrow\downarrow} + \omega_{\downarrow\uparrow}} = \frac{8\rho^3}{5\sqrt{3}c\lambda_c r_0 \gamma^5}$$

~ 1 hour at HERA

What if you need a Direct Source of Polarized Electrons?

TABLE III. Comparison of some sources of spin-polarized electrons.

Method	Ref.	$ P $	Reversal of \vec{P}	I_{dc} (A)	I_{pulse}	E (eV)	ΔE (eV)	H (kOe)	Emittance	Brightness
1. Photoemission from NEA GaAs	3	0.40	$\Delta\vec{L}$	10^{-6} [10^{-3}]	[10^{12} electrons/ 1.5 μ sec]	0.2	0.2	0	2 mrad-cm at 1 eV	very high
2. Photoemission from EuO	27	0.61 [0.80]	$\Delta\vec{H}$	10^{-6}	3×10^9 electrons/ 1.5 μ sec	2	2	21 [30]		medium
3. Photoionization of polarized Li atomic beam	53	0.76	$\Delta\vec{H}$		3×10^9 electrons/ 1.5 μ sec		1500	0.2	7 mrad-cm at 70 keV	medium
4. Fano effect, photoionization of Cs atoms	55	0.90	$\Delta\vec{L}$		3×10^9 electrons/ 0.5 μ sec		500	0	0.6 mrad-cm at 115 keV	high
5. Optically pumped He discharge	56	0.30	$\Delta\vec{L}$	10^{-6}		500 [30]	0.5	0	10 mrad-cm at 500 eV	high
6. Field emission (EuS)	57	0.89	$\Delta\vec{H}$	[10^{-6}]			0.1	2-20		very high
7. Electron scattering from Hg atomic beam	58	0.27	$\Delta\theta$	2×10^{-8}		7	0.2	0		medium
8. Electron scattering from W	62	0.40	$\Delta\theta, \Delta E$	5×10^{-8} [10^{-4}]		80	0.2	0		high

GaAs....the method that caught on

PHYSICAL REVIEW B

VOLUME 13, NUMBER 12

15 JUNE 1976

Photoemission of spin-polarized electrons from GaAs

Daniel T. Pierce* and Felix Meier

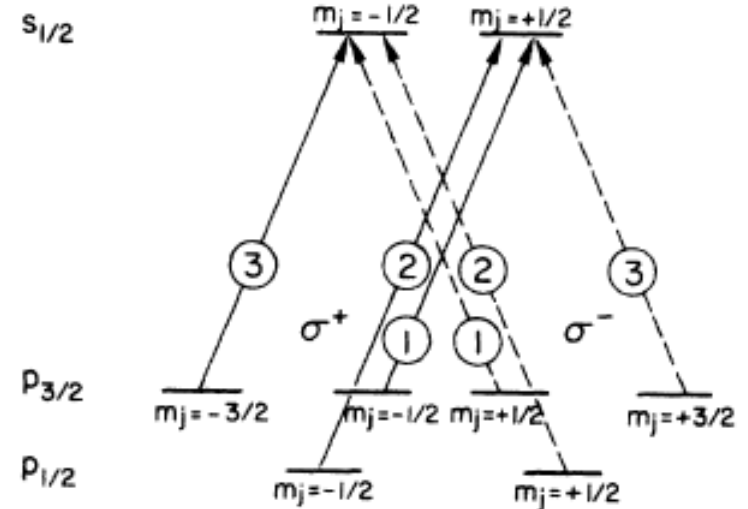
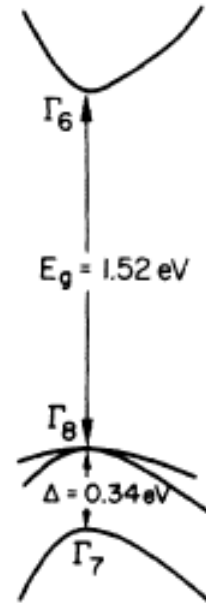
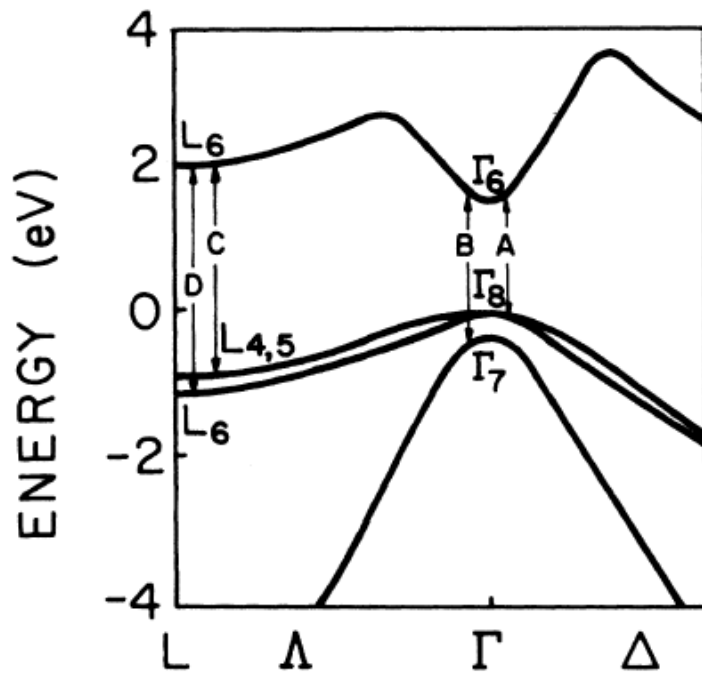
Laboratorium für Festkörperphysik, Eidgenössische Technische Hochschule, CH 8049, Zürich, Switzerland

(Received 10 February 1976)

The spin polarization of electrons photoemitted from (110) GaAs by irradiating with circularly polarized light of energy $1.5 < \hbar\omega < 3.6$ eV was measured by Mott scattering. The GaAs surface was treated with cesium and oxygen to obtain a negative electron affinity (NEA). The spectrum of spin polarization $P(\hbar\omega)$ exhibits a peak ($P = 40\%$) at threshold arising from transitions at Γ , and positive ($P = 8\%$) and negative ($P = -8\%$) peaks at 3.0 and 3.2 eV, respectively, arising from transitions at L (Λ). Anomalous behavior, consisting of a depolarization at threshold and an increase and shift in the peak polarization to 54% at 1.7 eV, is attributed to a small positive electron affinity (PEA) characteristic of some samples. Restriction of the photoelectron emission angle by the PEA leads directly to the anomalously high P . Results of calculations show that P cannot be increased above 50% for emission arising from transitions at Γ in NEA GaAs. Our detailed interpretation of the spectra indicates how spin-polarized photoemission can be used to study the spin-dependent aspects of electronic structure. The outstanding qualities of NEA GaAs as a source of spin-polarized electrons are discussed and compared with other sources.

GaAs Energy Levels

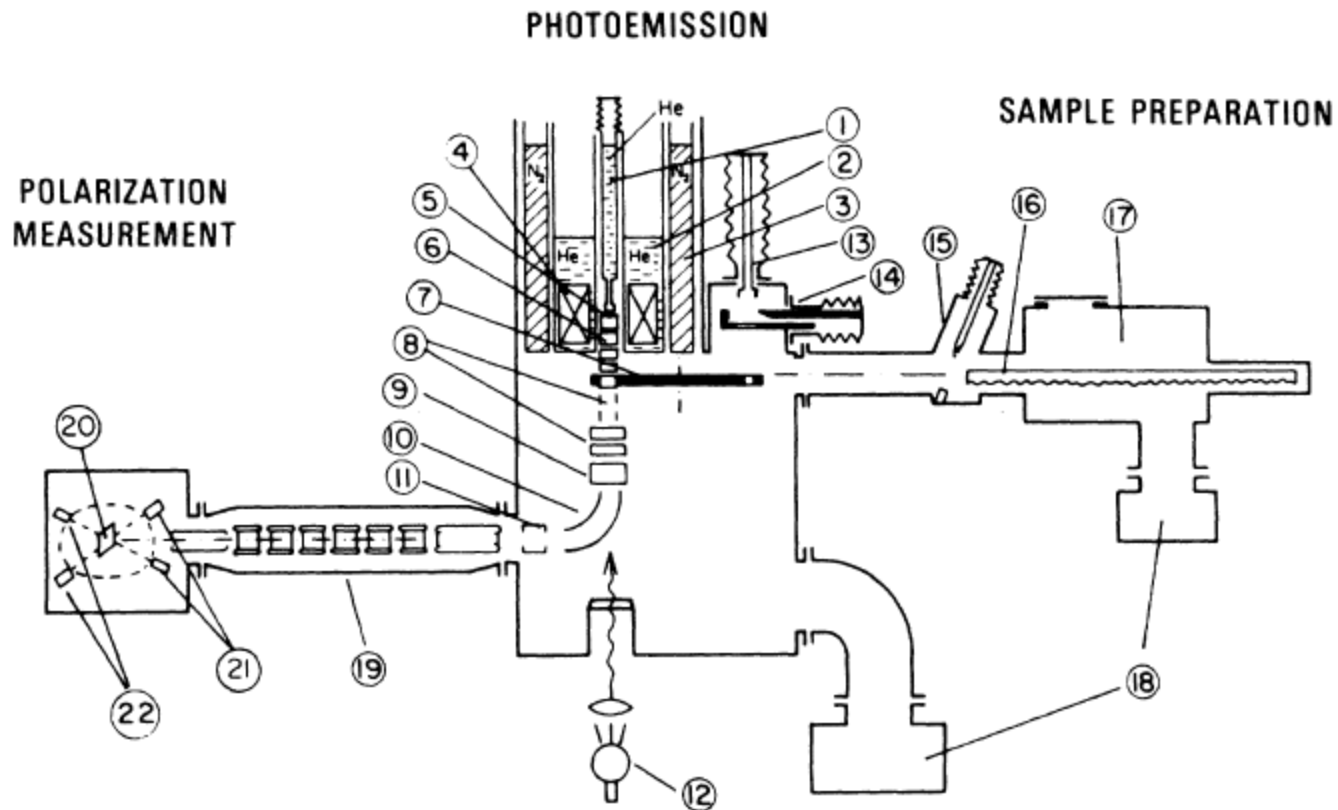
First proposed by Garwin, Pierce, Siegmann and Lampel and Weisbuch



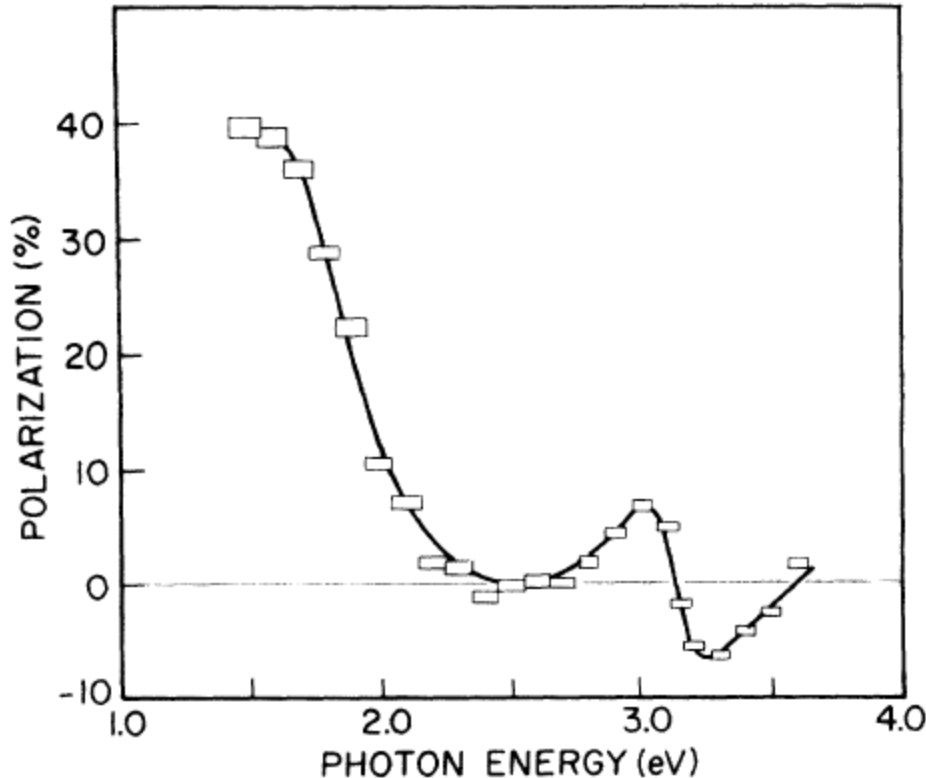
$$P_e = \frac{N_{\uparrow} - N_{\downarrow}}{N_{\uparrow} + N_{\downarrow}} = \frac{3 - 1}{3 + 1} = 50\%$$

- Energy versus momentum
- GaAs is a “Direct” transition semiconductor
- Valence band P-state split due to spin-orbit coupling
- m_j quantum numbers describe electron’s spin and orbital angular momentum
- Quantum mechanical selection rules dictate $\Delta m_j = \pm 1$ for absorption of circularly polarized light
- Clebsch-Gordon coefficients indicate the relative likelihood of transitions between states

Pierce-Meier Apparatus

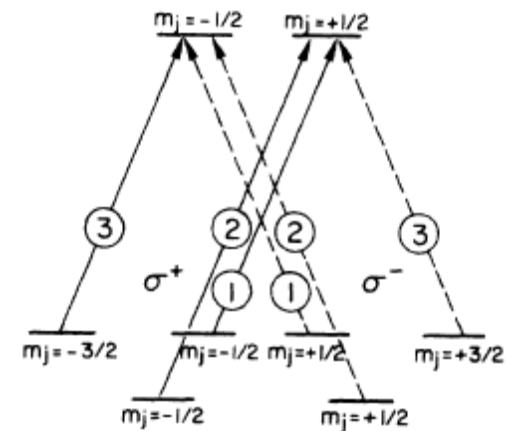


First Observation of Polarization



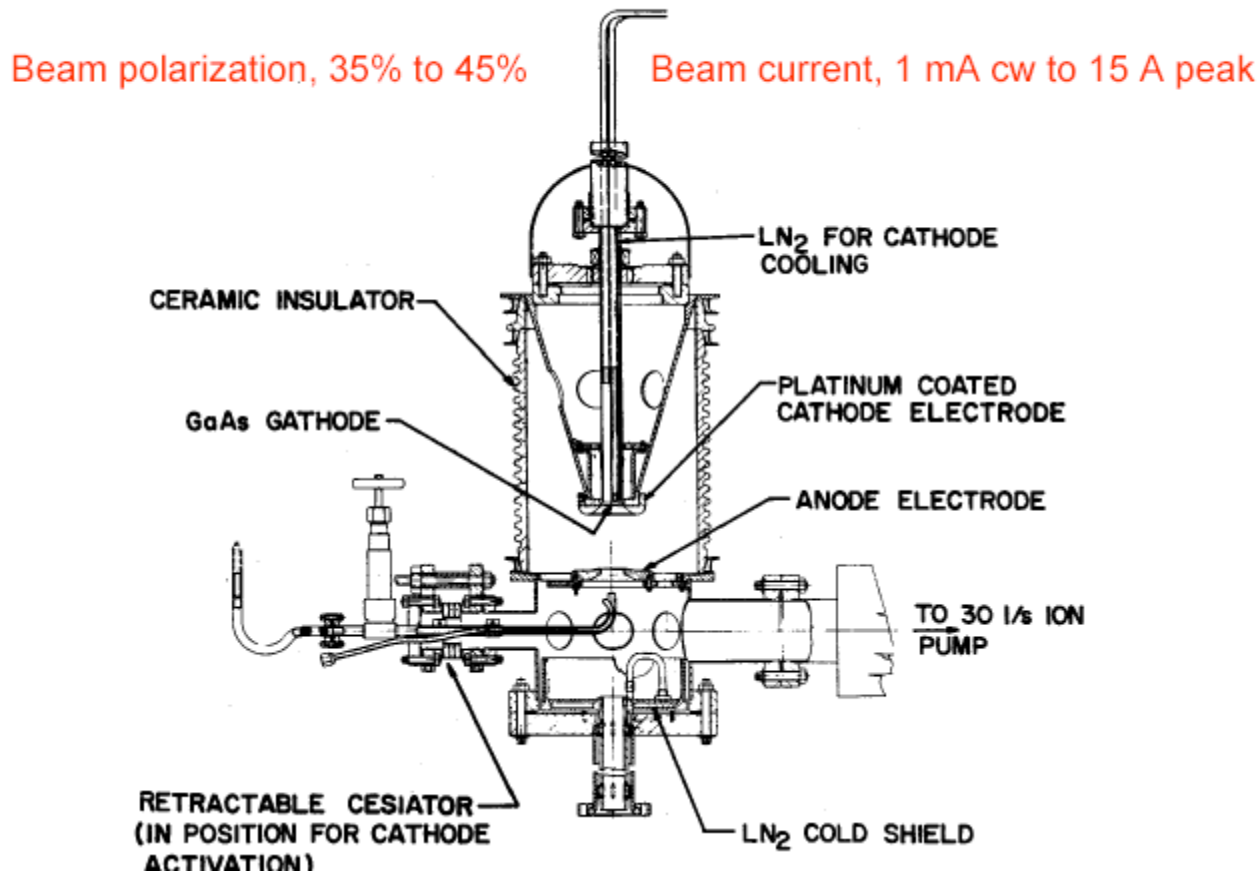
- Maximum polarization not 50%
- Note interesting non-zero polarization sub-peaks at 3.0 eV and 3.2 eV
- Flip the sign of polarization by flipping the polarity of the light

FIG. 6. Spectrum of spin polarization from GaAs + CsOCs at $T \leq 10$ K [the same sample and conditions as curve (a) of Fig. 5]. Note the high value of $P=40\%$ at threshold ($\hbar\omega \sim 1.5$ eV) and positive and negative peaks at $\hbar\omega = 3.0$ and 3.2 eV.



First High Voltage GaAs Photogun

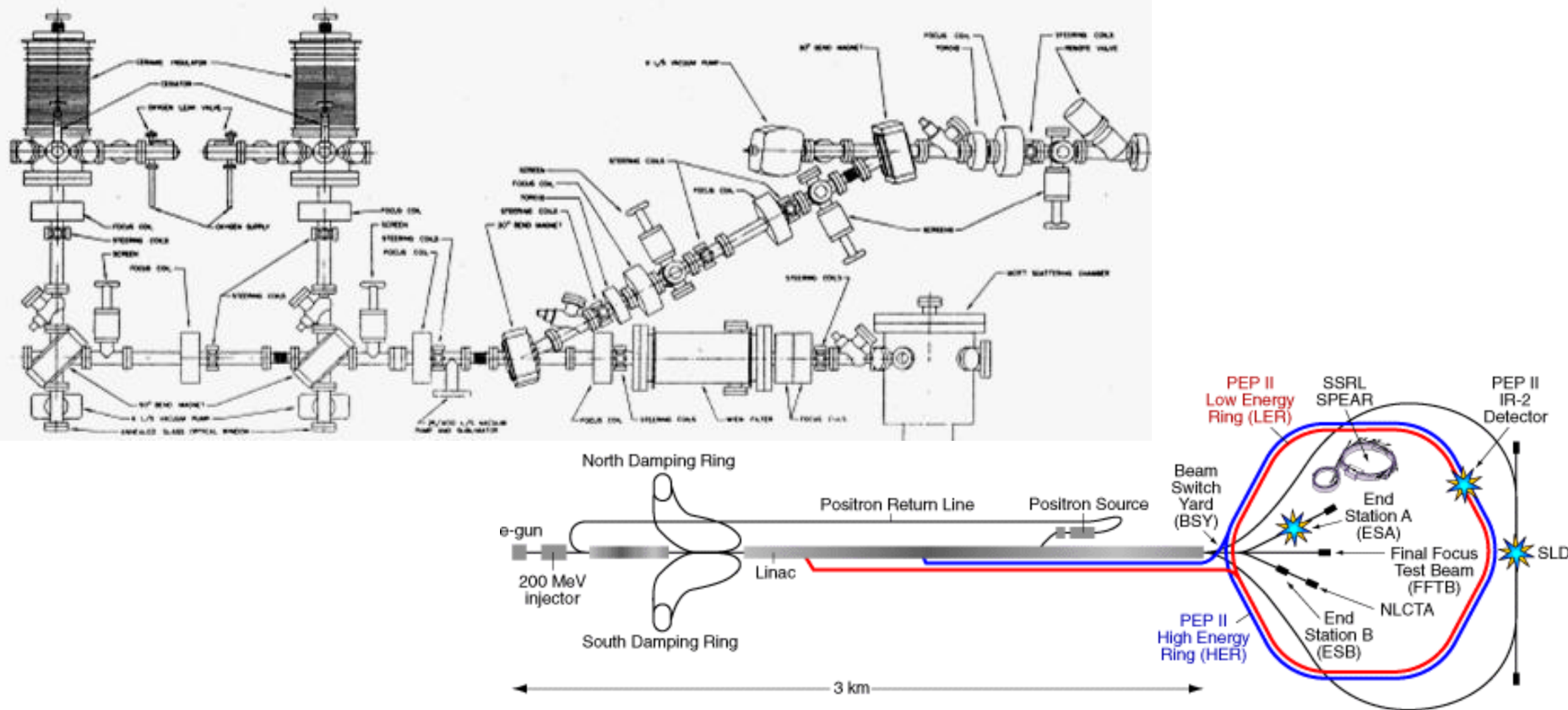
Polarized e⁻ Gun for SLAC Parity Violation Experiment



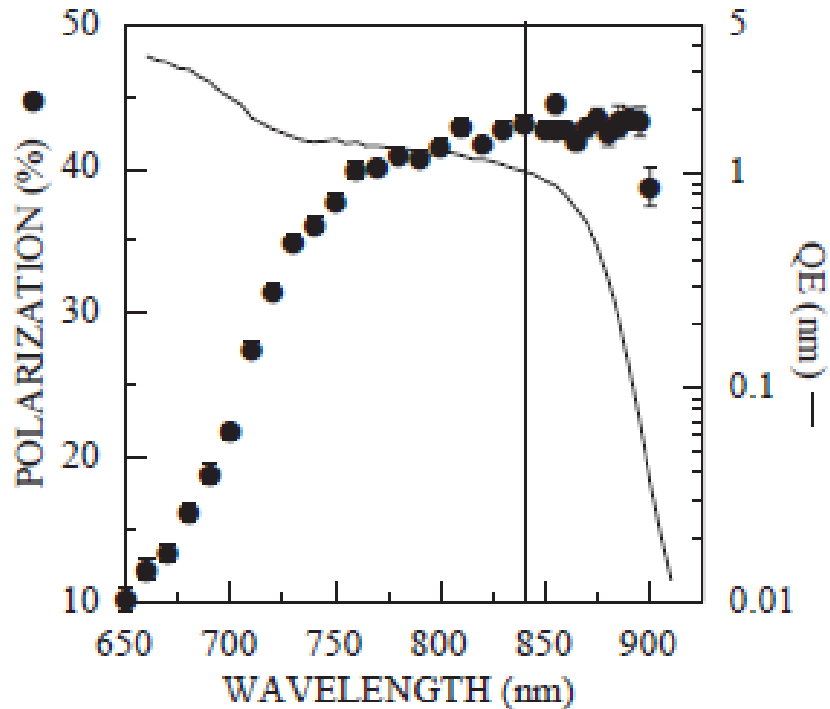
Started with a thermionic gun housing?

First GaAs Photoinjector

- Built for SLAC parity-violation experiment E122
- Polarized electrons accelerated December, 1977
- E122 announces parity violation June, 1978 - an important verification of the Standard Model

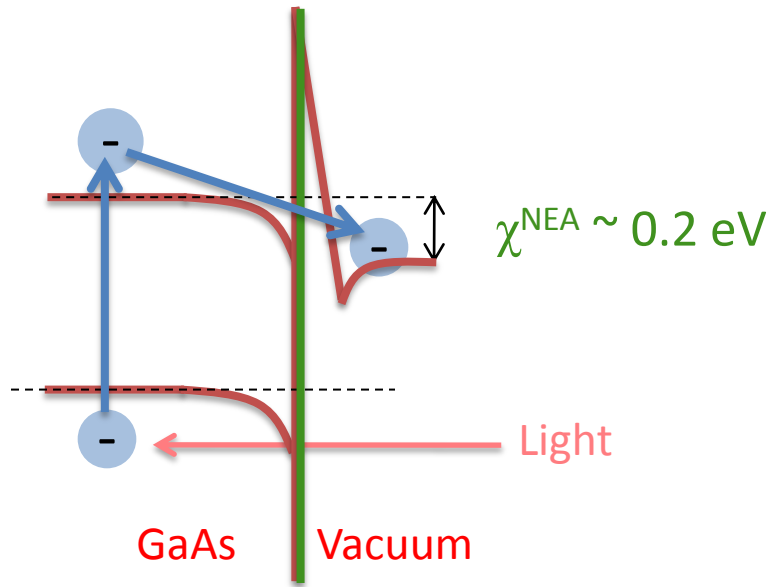


Typical bulk GaAs Result



- QE at bandgap (i.e., where you get highest polarization) can be 10% or more

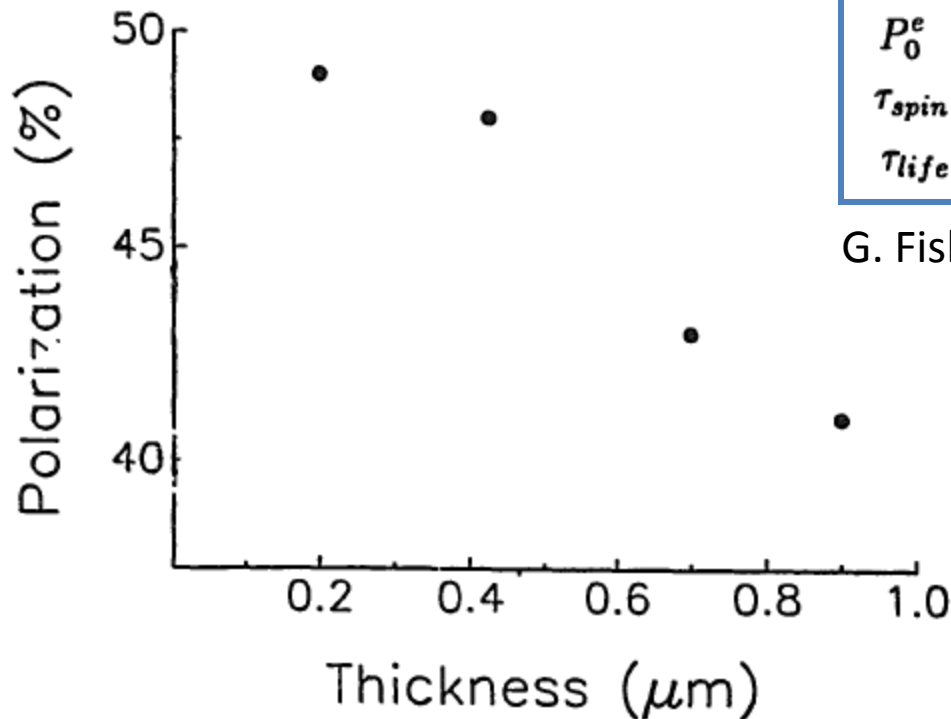
Depolarization Mechanisms



Time scales for these depolarization processes are roughly equal to the lifetime of the electron in the conduction band, $\sim 200\text{ps}$. Therefore, it is very important to get the polarized electrons out of the material as quickly as possible

- BAP Process: the exchange interaction between electrons and holes (after G. L. Bir, A. G. Aronov and G. E. Picus)
- DP Process: the dynamic narrowing of the magnetic resonance in spin-orbit split-off conduction bands (after M. I. Dyakonov and V. I. Perel)
- EY process in which the spin-orbit interaction generates non-pure spin states in the conduction band (after R. J. Elliot and Y. Yafet)
- Radiation Trapping, where recombination radiation is re-absorbed producing unpolarized photoemission

What limits polarization?



Maruyama et al., Appl. Phys. Lett., 55, 1686 (1989)

Absorption depth $\sim 1\mu\text{m}$ in GaAs

$$P_{obs}^e = \frac{\tau_{spin}}{\tau_{spin} + \tau_{life}} P_0^e \quad \text{where:}$$

P_{obs}^e = the observed spin polarization;

P_0^e = the spin polarization before relaxation;

τ_{spin} = the spin relaxation time; and

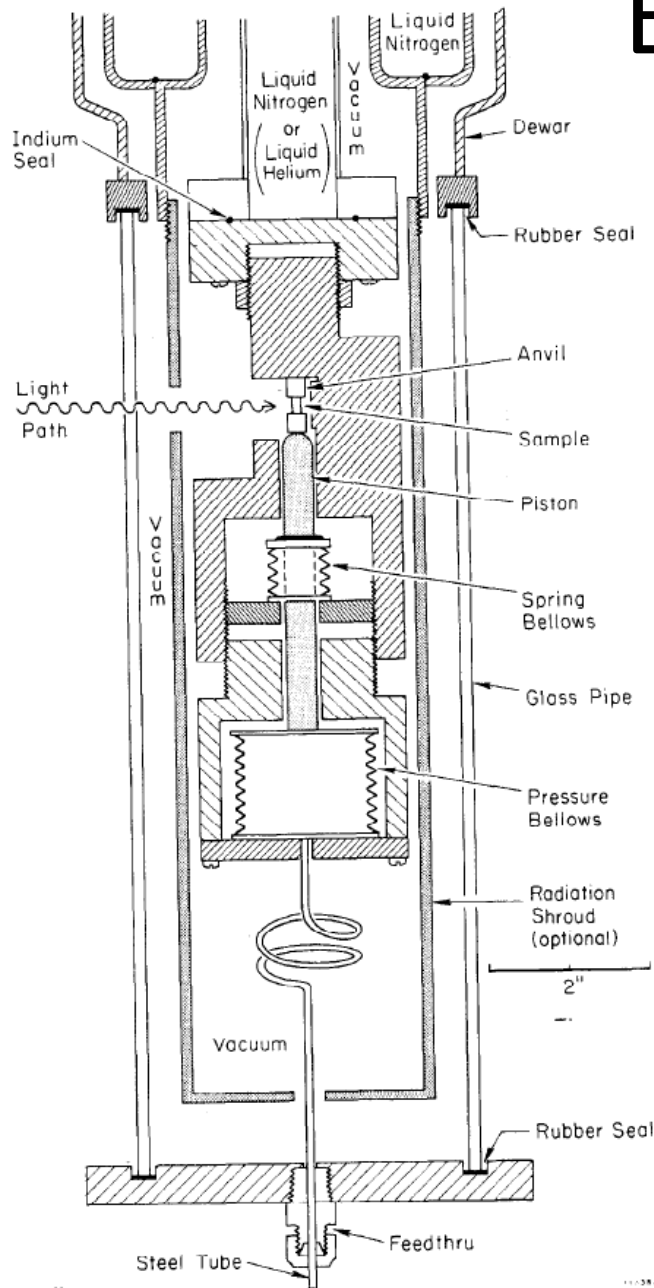
τ_{life} = the lifetime of conduction band electrons.

G. Fishman and G. Lampel, Phys Rev. B16, 820 (1977)

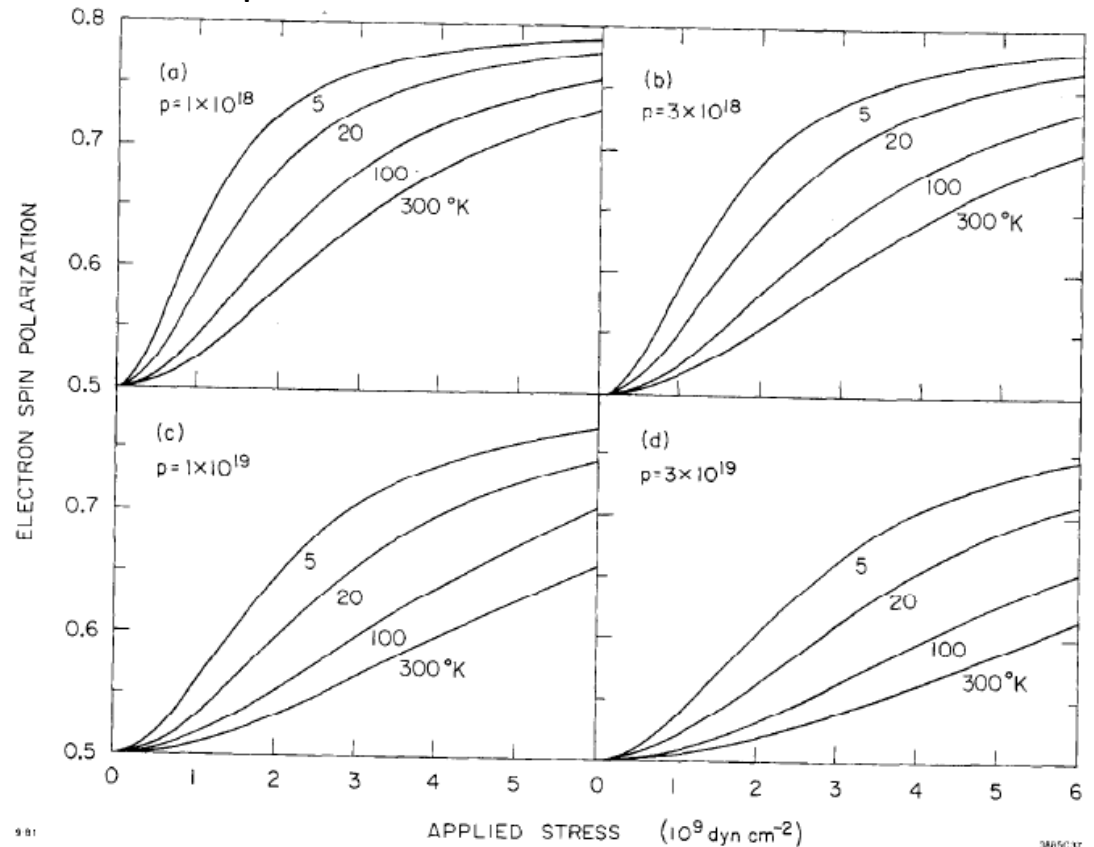
Polarization lost as electrons diffuse to the surface: thin samples provide higher polarization, at expense of QE

Breaking the 50% barrier

PhD thesis, Paul Zorabedian, SLAC Report 248, 1982



Electron polarization inferred from photoluminescence measurements



Compress the GaAs crystal in hydraulic press!
Hard to keep the GaAs sample from shattering

Eliminate degeneracy of $P_{3/2}$ state via “Interface Stress Method”

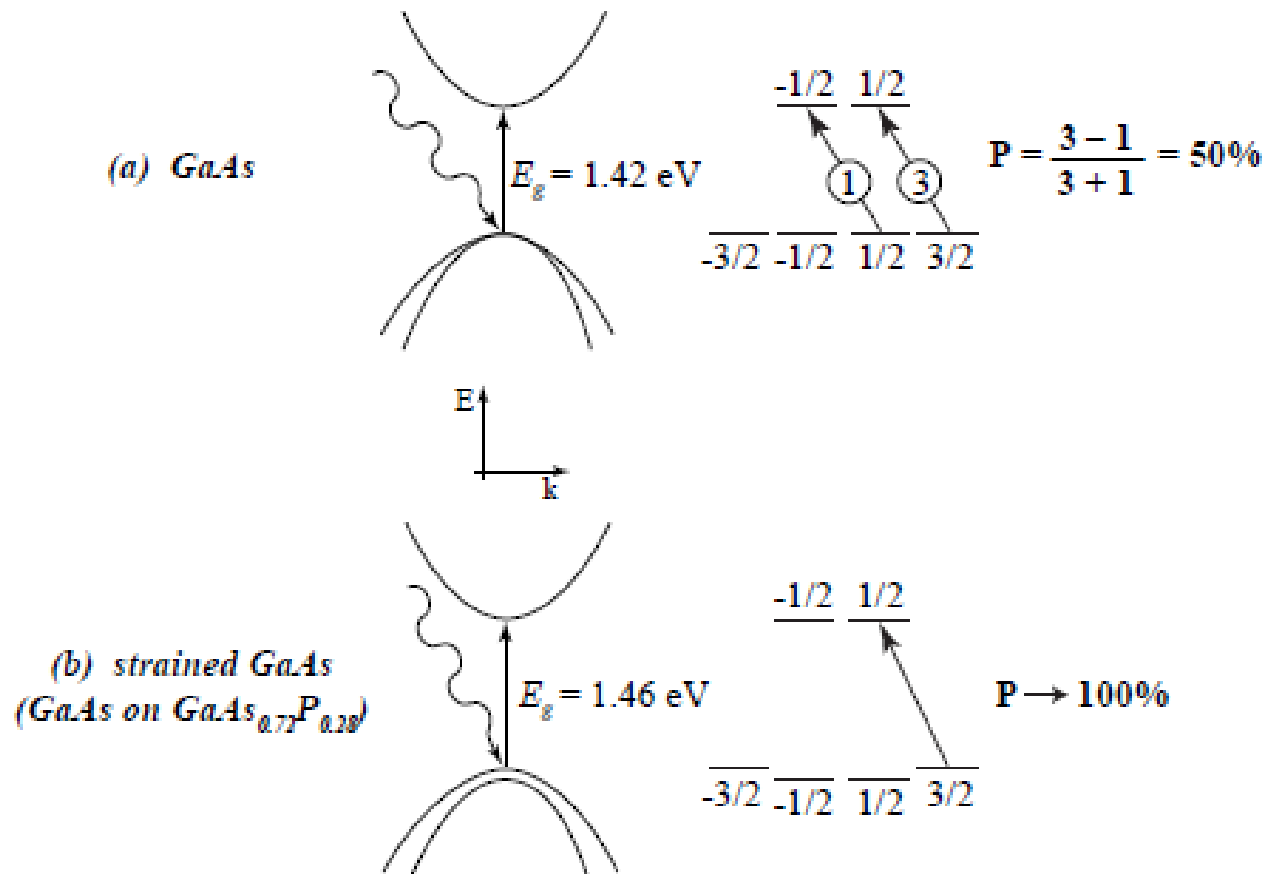
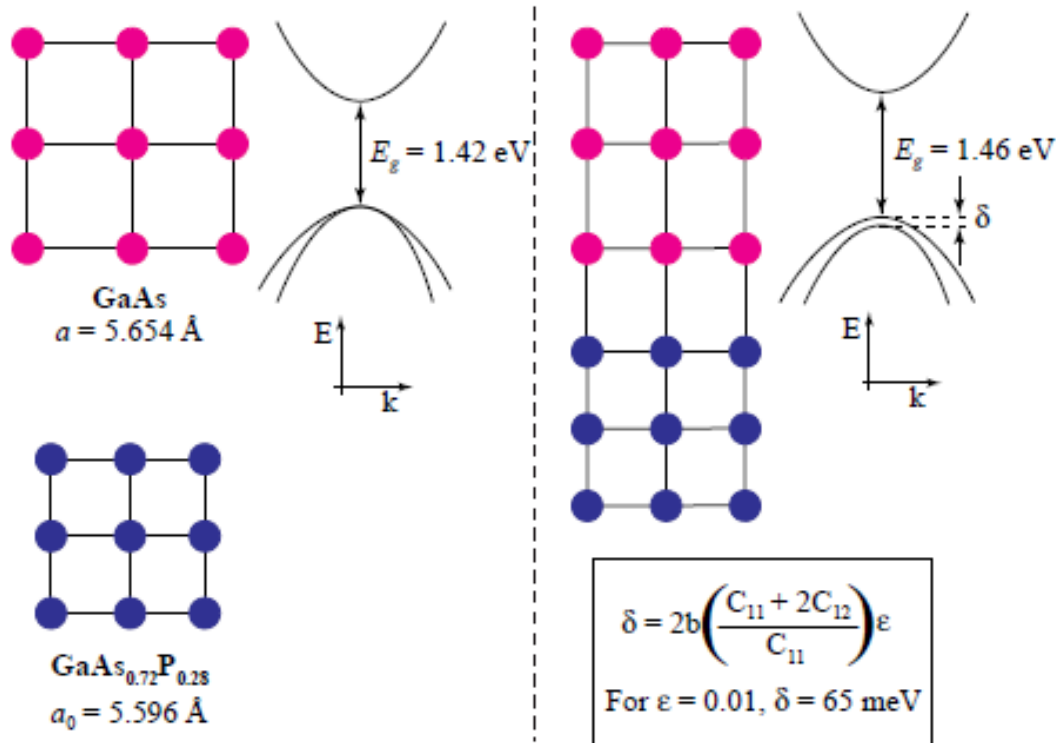


Image from Pablo Saez, PhD Thesis, Stanford University, SLAC Report 501, 1997

Lattice mismatch provides stress



- The band gap of the substrate layer must be larger than surface layer
- Lattice constants must differ enough to introduce suitable strain
- Adjust lattice constant of substrate by varying concentration of third element

Pablo Saez, PhD Thesis, SLAC Report 501, 1997

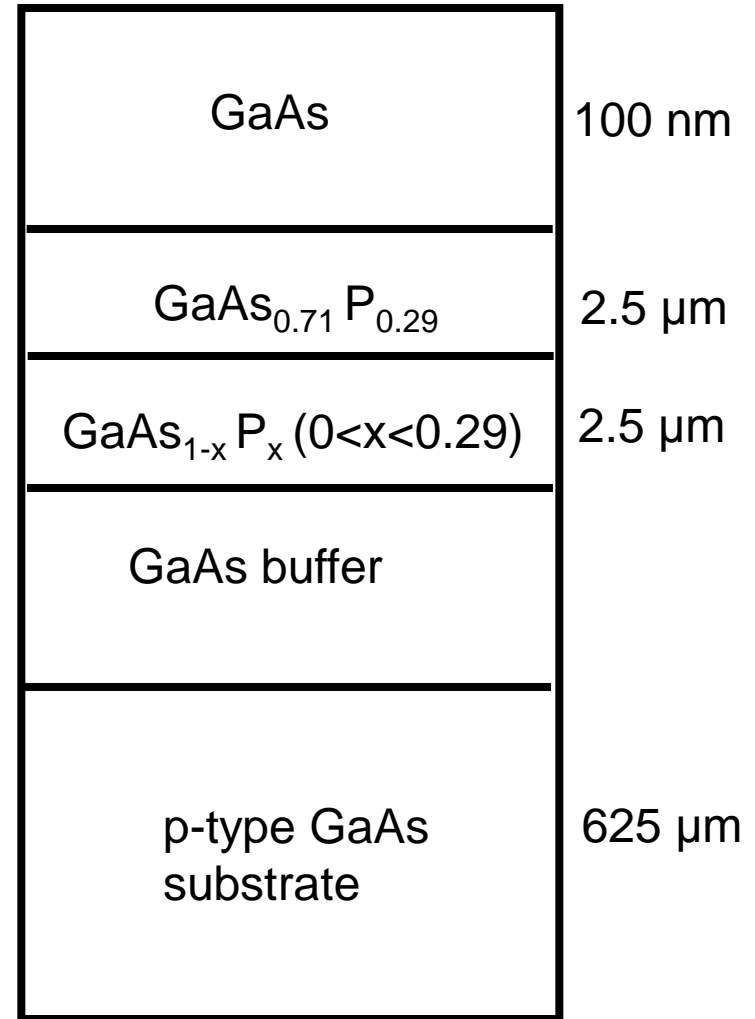
$$\delta_s = 6.5 \left(\frac{\Delta a}{a_0} \right) (eV)$$

1% lattice mismatch provides equivalent force as hydraulic press!

Strained-layer GaAs

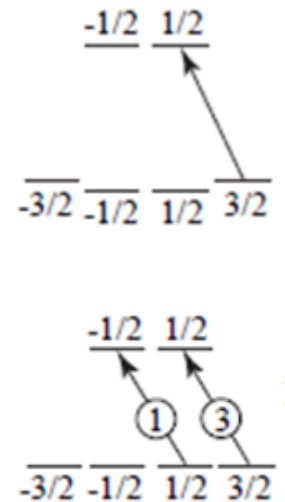
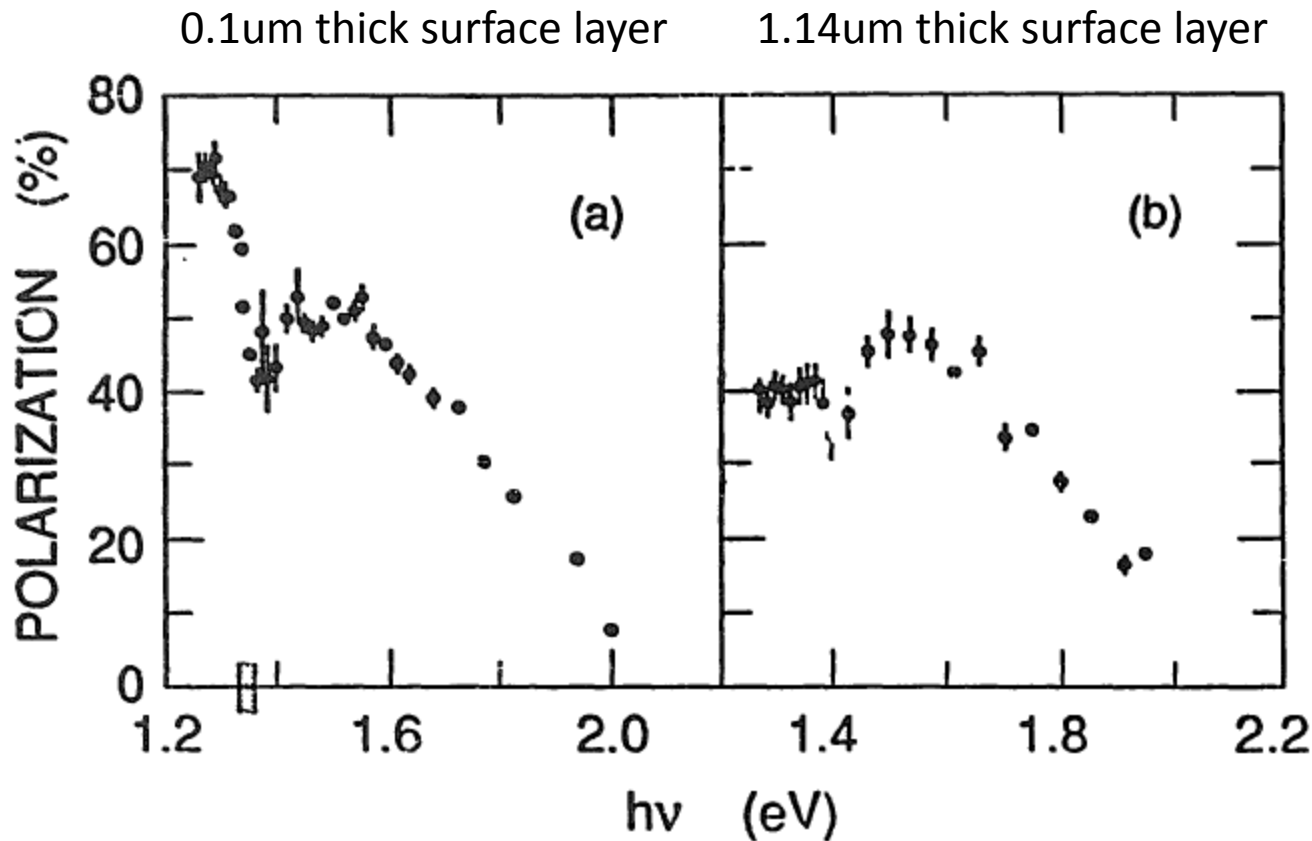
Zn dopant
 $\sim 5 \cdot 10^{18}$
(cm^{-3})

- MOCVD-grown epitaxial spin-polarizer wafer
- Polarization $\sim 75\%$ at $\sim 850\text{nm}$
- QE $\sim 0.1\%$
- Available from Bandwidth Semiconductor
- 3" dia. wafer $\sim 10\text{k}\$$
- Developed via DOE-SBIR program



Manufactured by Bandwidth Semiconductor

First Strained GaAs Result



$\text{In}_x\text{Ga}_{1-x}\text{As}$ grown on GaAs substrate ($x = 0.13$)

Maruyama et.al., Phys. Rev. Lett., 66, 2376 (1991)

Getting the Recipe Right

- Choice of Surface layer
- Choice of Substrate layer
- Tensile vs compressive strain?
- What is correct lattice mismatch?
- How thick to make the active layer?

Periodic Table (Detail)

	Group				
	II	III	IV	V	VI
2	9.0 Be 4	10.8 B 5	12.0 C 6	14.0 N 7	16.0 O 8
3	24.3 Mg 12	27.0 Al 13	28.1 Si 14	31.0 P 15	32.1 S 16
4	40.1 Ca 20	69.7 Ga 31	72.6 Ge 32	74.9 As 33	79.0 Se 34
5	87.6 Sr 38	114.8 In 49	118.7 Sn 50	121.8 Sb 51	127.6 Te 52
6	137.3 Ba 56	204.4 Tl 81	207.2 Pb 82	209.0 Bi 83	209 Po 84

Al = Aluminium

Ga = Gallium

In = Indium

N = Nitrogen

P = Phosphorus

As = Arsenic

Sb = Antimony

Getting the Recipe Right

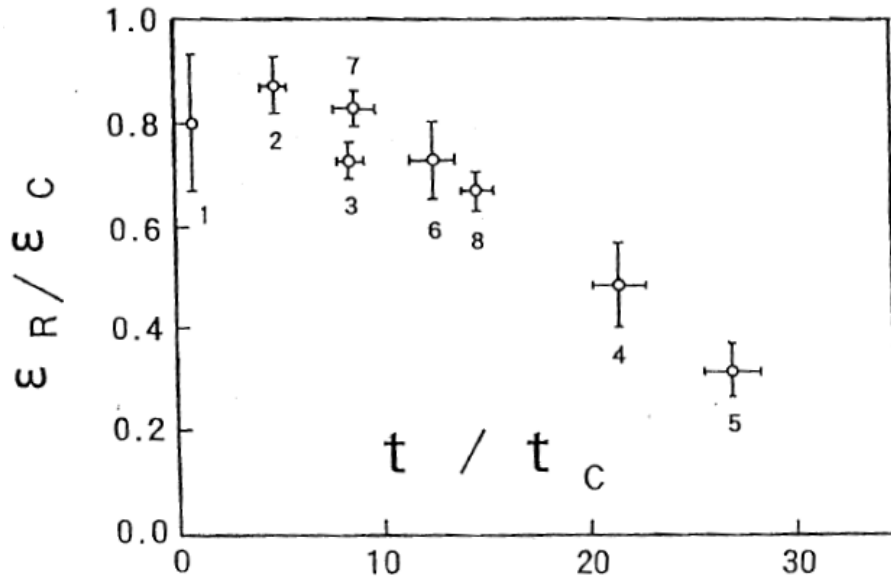
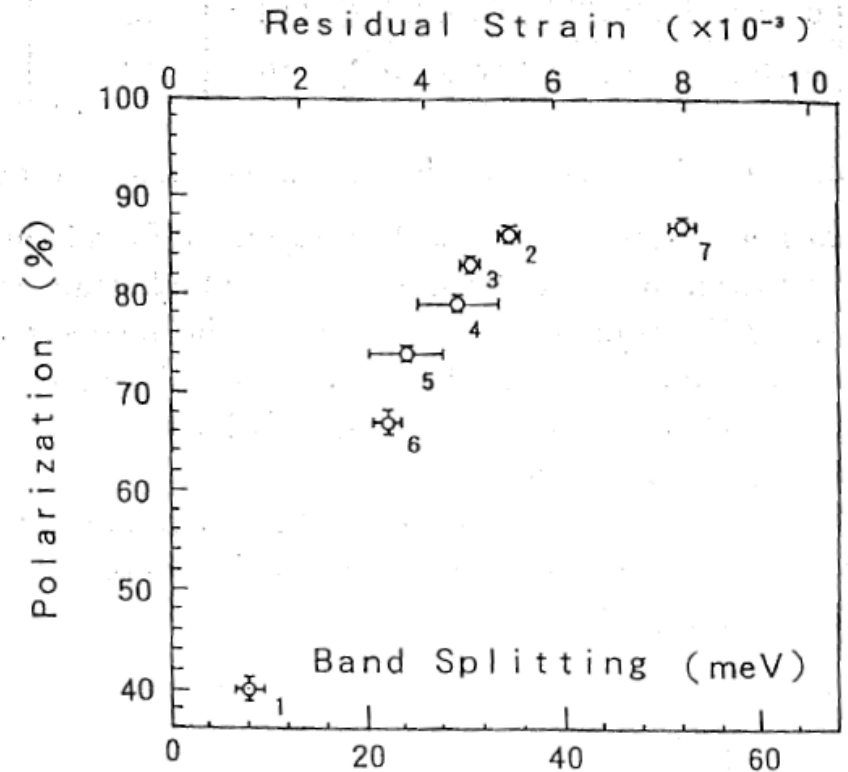


Fig. 1. Strain relaxation in GaAs layers



g. 2. Strain dependence of the maximum polarization

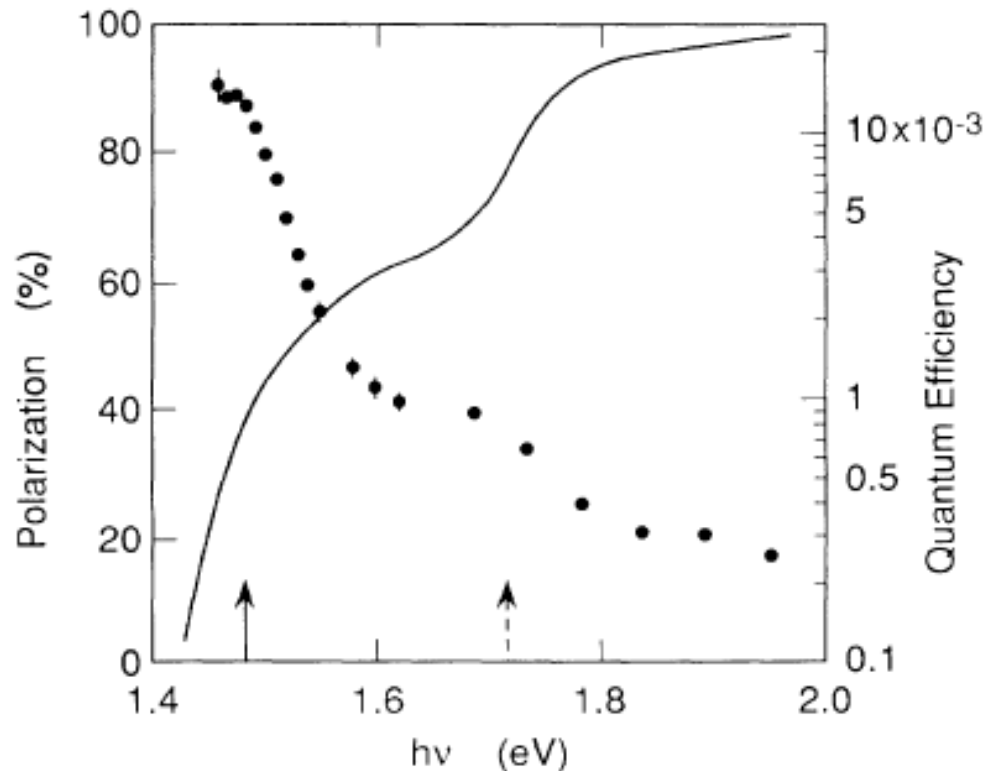
- Thickness can be 10x greater than t_c
- Band splitting needs to be > 30 meV

Higher Polarizations Followed

GaAs grown on top of $\text{GaAs}_{1-x}\text{P}_x$ substrate

GaAs thickness $\sim 0.1 \mu\text{m}$ and $x = 0.29$, **lattice mismatch $\sim 1\%$**

This became the standard SPIN Polarizer wafer sold by SPIRE, now
Bandwidth Semiconductor

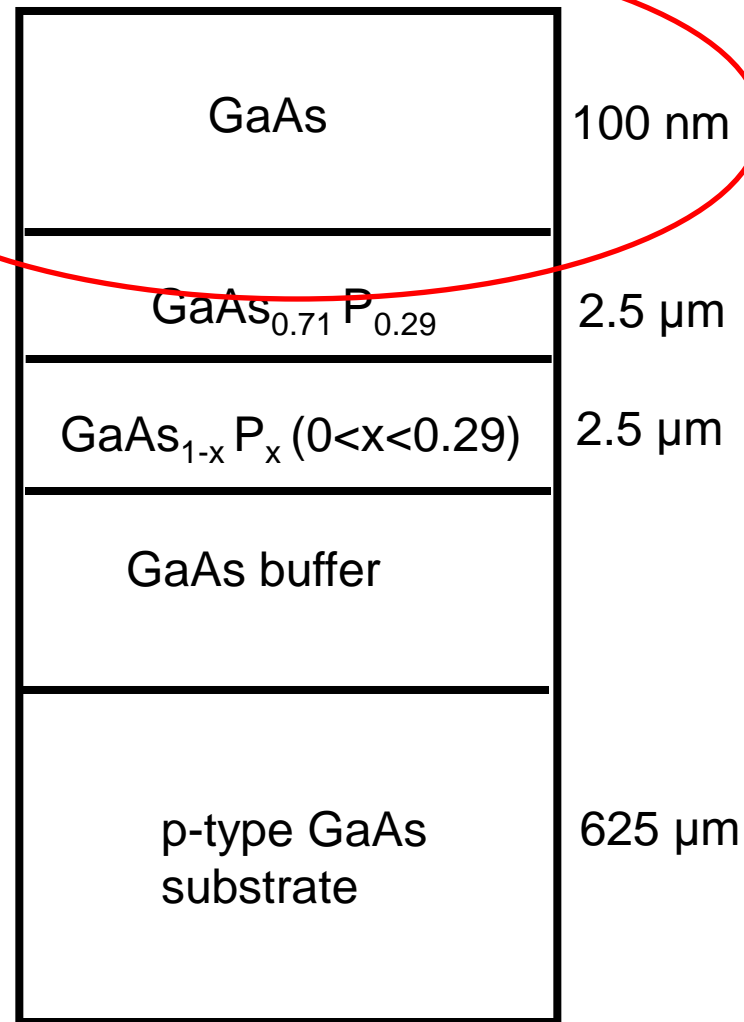


Maruyama et al., Phys. Rev. B., 46, 4261 (1991)

Strained-layer GaAs

Zn dopant
 $\sim 5 \cdot 10^{18}$
(cm^{-3})

- MOCVD-grown epitaxial spin-polarizer wafer
- Polarization $\sim 75\%$ at $\sim 850\text{nm}$
- QE $\sim 0.1\%$
- Available from Bandwidth Semiconductor
- 3" dia. wafer $\sim 10\text{k}\$$
- Developed via DOE-SBIR program



Manufactured by Bandwidth Semiconductor

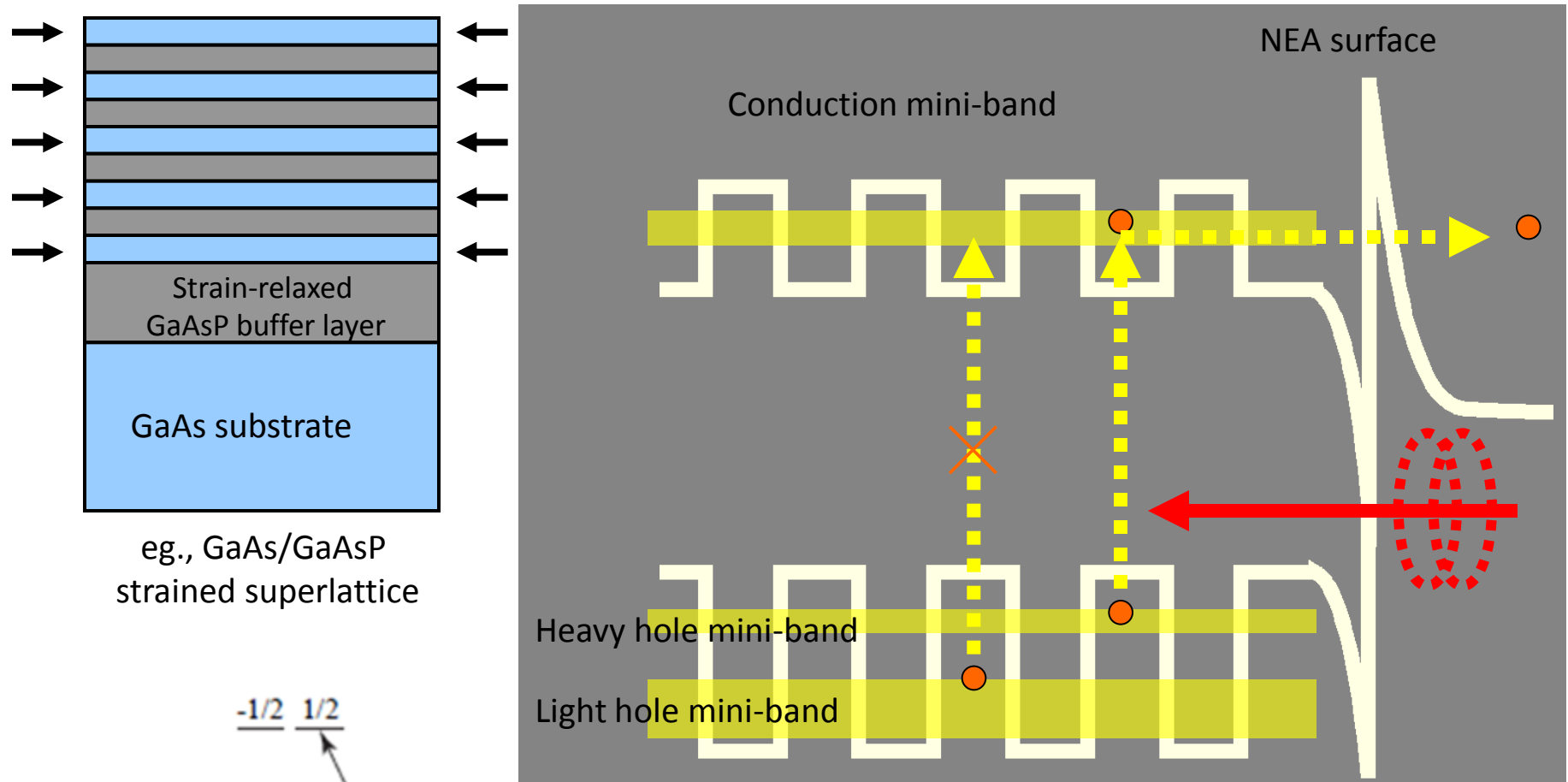
Higher P, Higher QE?

- Problem: Strained layers start relaxing beyond thickness $\sim 10\text{nm}$. Strained layer practical limit $\sim 100\text{nm}$
 - Strain relaxation \rightarrow Lower polarization
 - Thin layer \rightarrow Lower QE
- So how to get Higher Polarization and Higher QE?
- Solution: Use many thin strained layers – ***Strained Superlattice Photocathode...***

Strained Superlattice Photocathode

Electrons tunnel through very thin buffer layers!!

Slide courtesy Toru Ujihara, PESP 2008

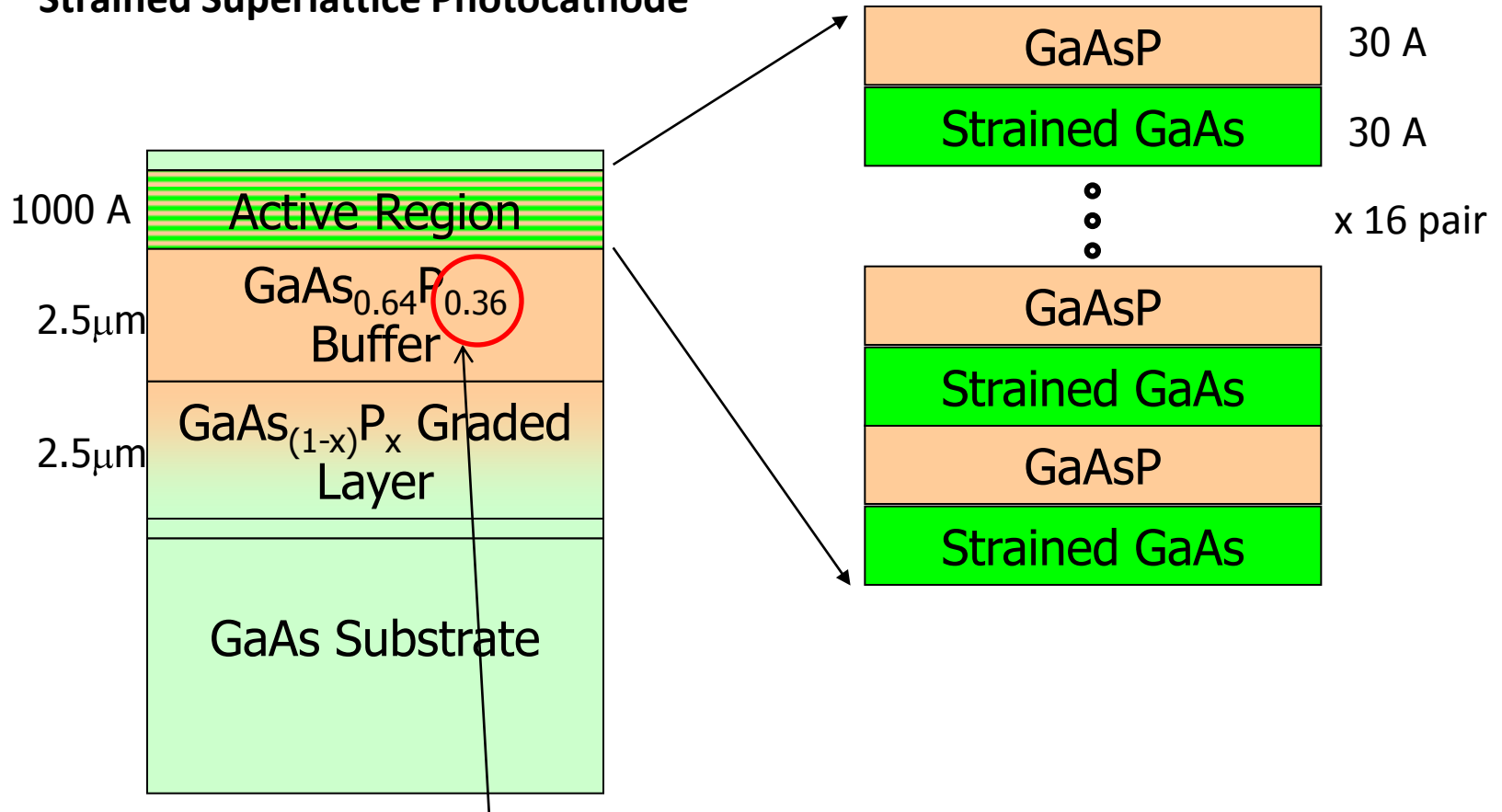


$\frac{-1/2}{-3/2} \quad \frac{1/2}{-1/2} \quad \frac{1/2}{1/2} \quad \frac{3/2}{3/2}$

It is important that electrons are excited
ONLY FROM HEAVY-HOLE MINI-BAND

Getting the Recipe Right

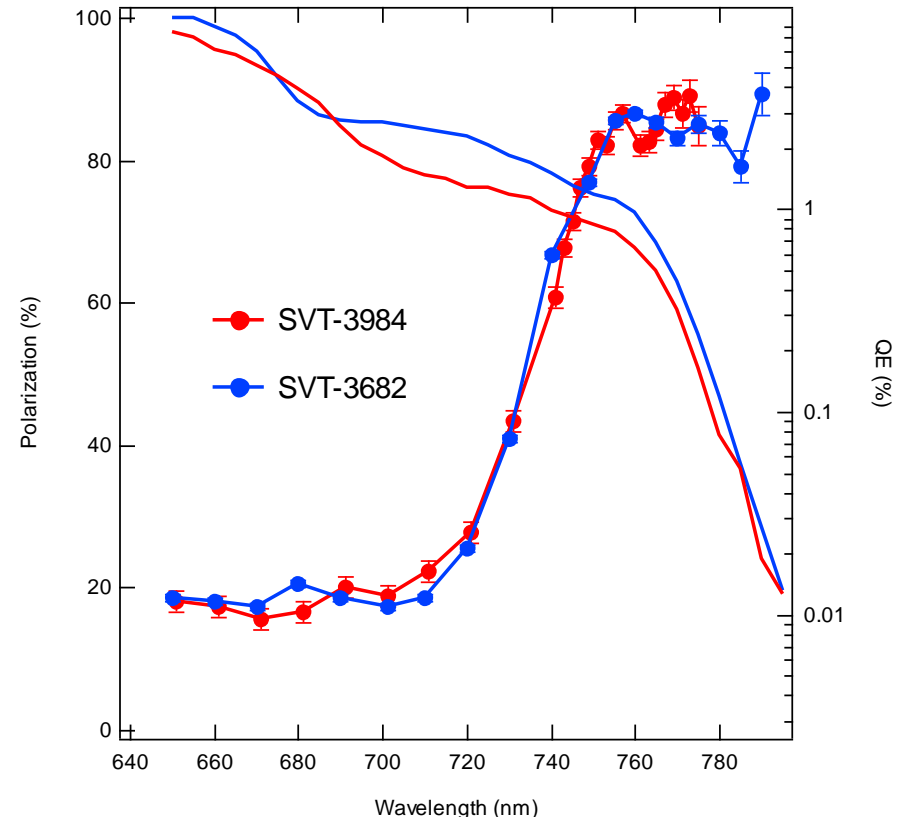
Strained Superlattice Photocathode



Notice more [P] → more strain, more $P_{3/2}$ state splitting, higher Pol

Higher Polarization AND Higher QE

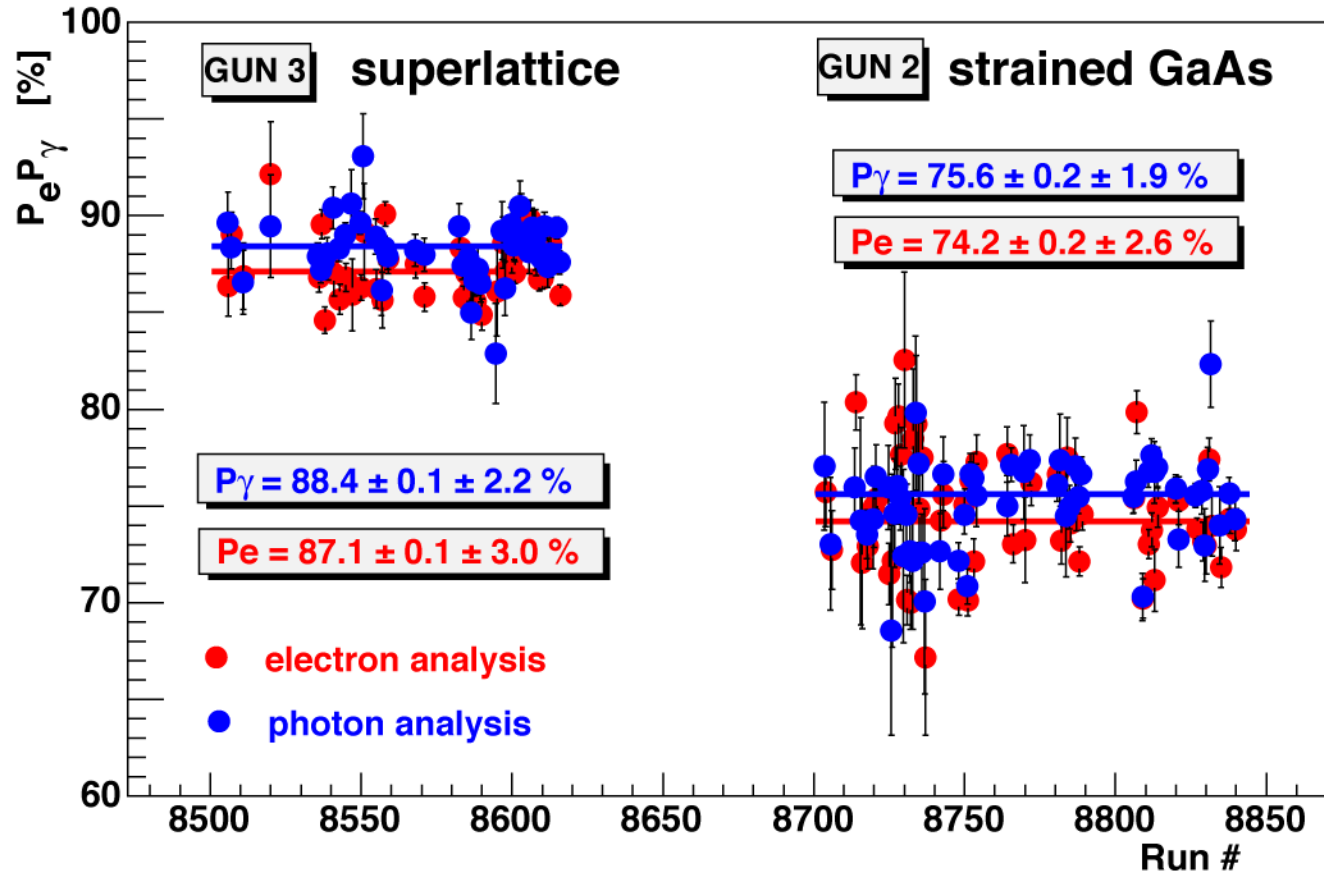
- MBE-grown epitaxial spin-polarizer wafer
- Pol $\sim 85\%$ at $\sim 780\text{nm}$
- QE $\sim 1\%$
- Available from SVT Associates
- 2" dia. wafer $\sim 10\text{k}\$$
- Developed via DOE-SBIR program



D. Luh et al, SLAC, PESP2002

Significant FOM Improvement

HAPPEx-II 2004 run Compton Polarimetry



$$FOM\ Improvement = \frac{P_{ssl}^2 I}{P_{sl}^2 I} = 1.38$$

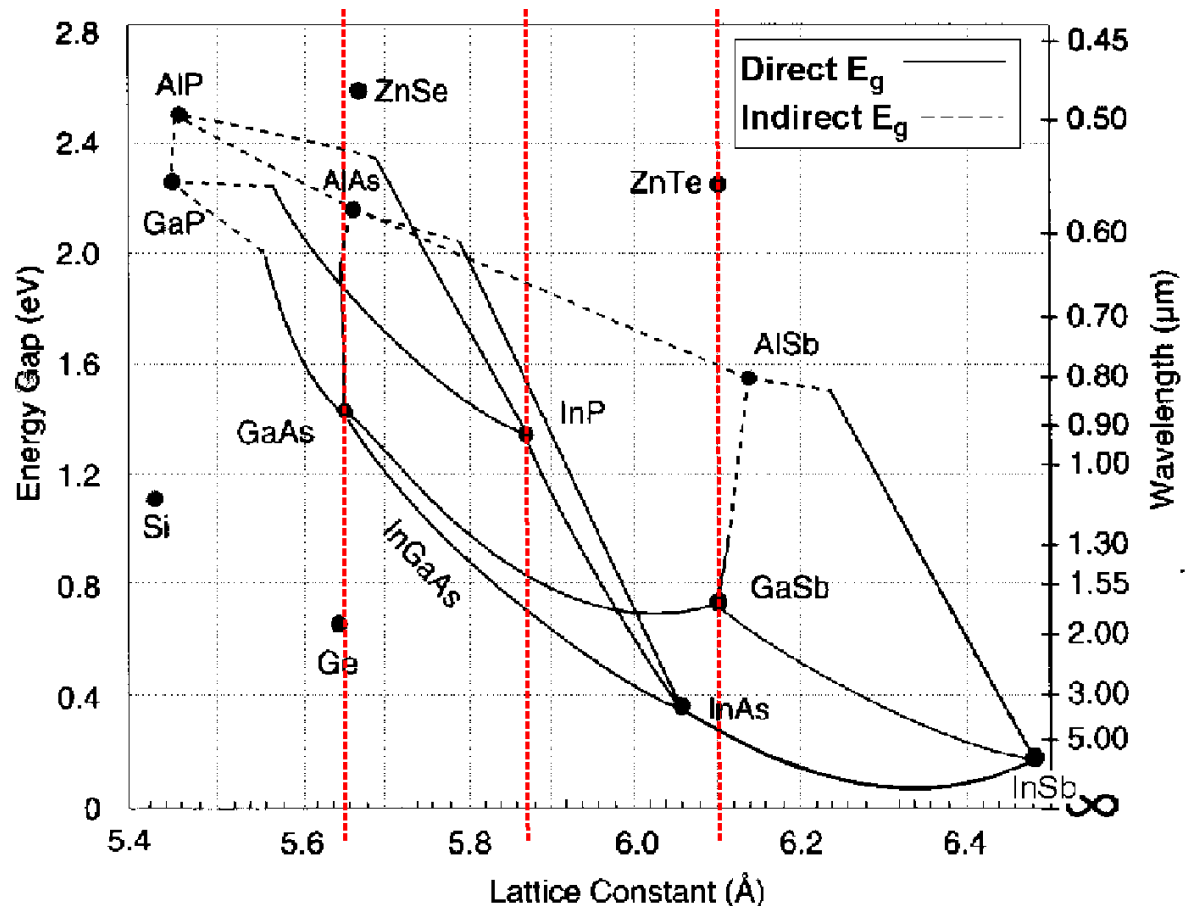
This means it takes less time to do an experiment with same level of statistical accuracy

Still Tweaking the Recipe

III-V Compound Semiconductors

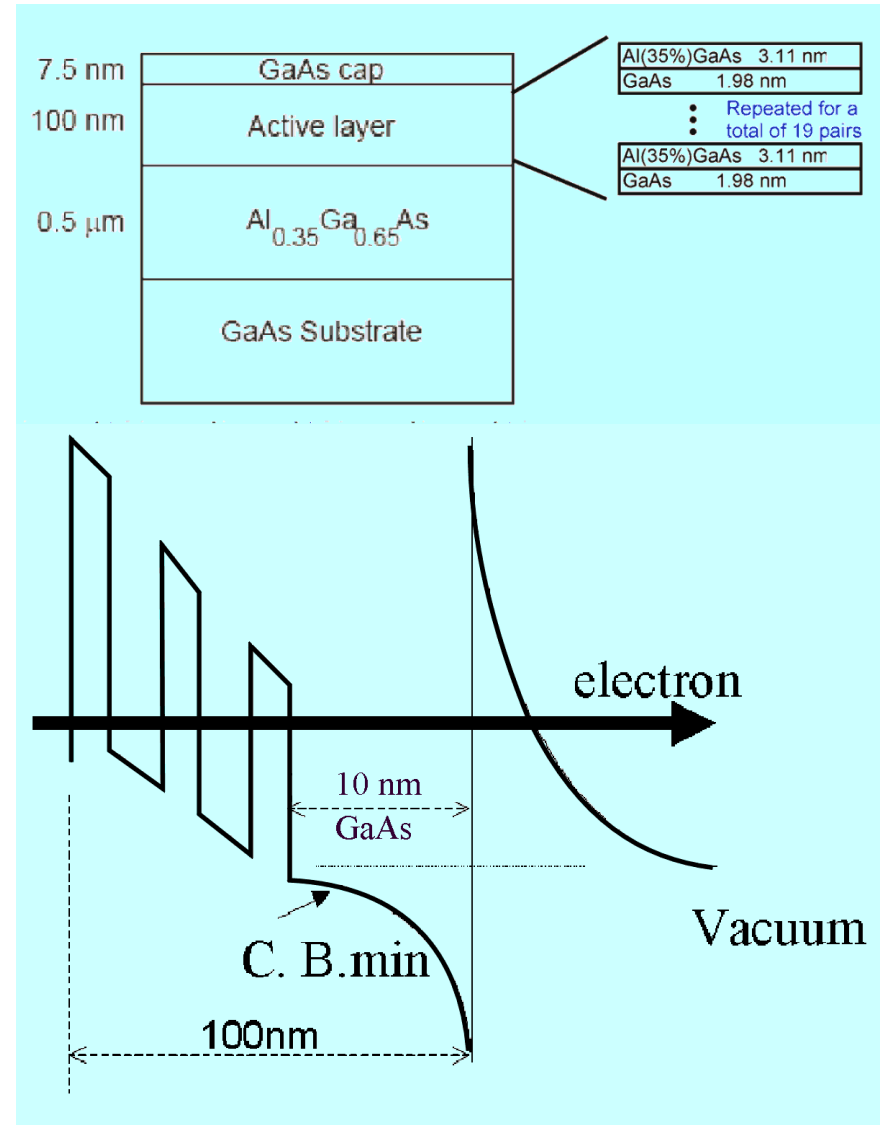
III	IV	V	VI	VII	VIII
B	C	N	O	F	He
Al	Si	P	S	Cl	Ar
Ga	Ge	As	Se	Br	Kr
In	Sn	Sb	Te	I	Xe
Tl	Pb	Bi	Po	At	Rn

Still looking for combinations that provide
Higher Polarization,
Higher QE, more rugged lifetime



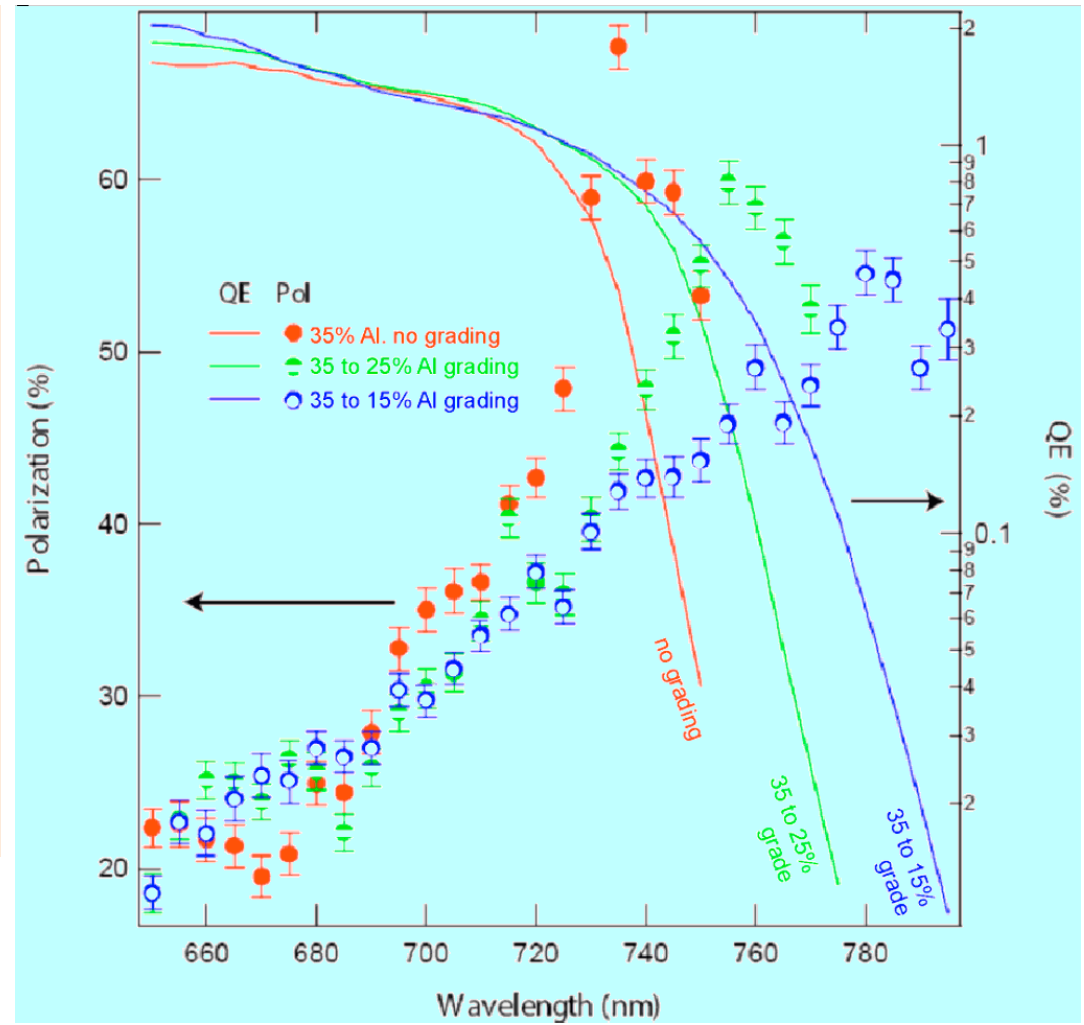
Internal Gradient Strained-Superlattice

- Photocathode active layers with internal accelerating field
- Internal field enhances electron emission for higher QE
- Less transport time also reduces depolarization mechanisms
- Gradient created by varied alloy composition or dopant profile



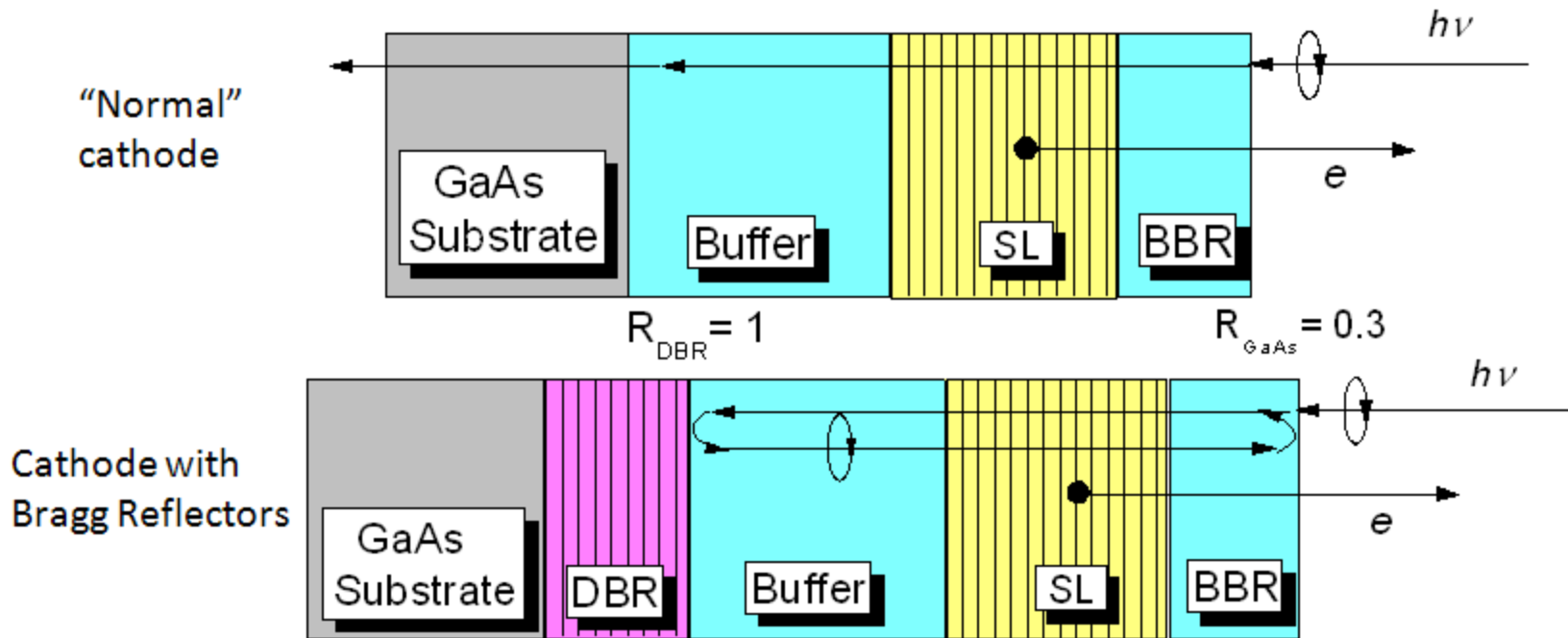
Internal Gradient GaAs/AlGaAs SLs

- Polarization decreased as aluminum gradient increased
- Due to less low LH-HH splitting at low aluminum %
- QE increased 25% due to internal gradient field
- Peak polarization of 70 % at 740 nm, shorter than 875 nm of GaAs



DBR – Equipped Crystal

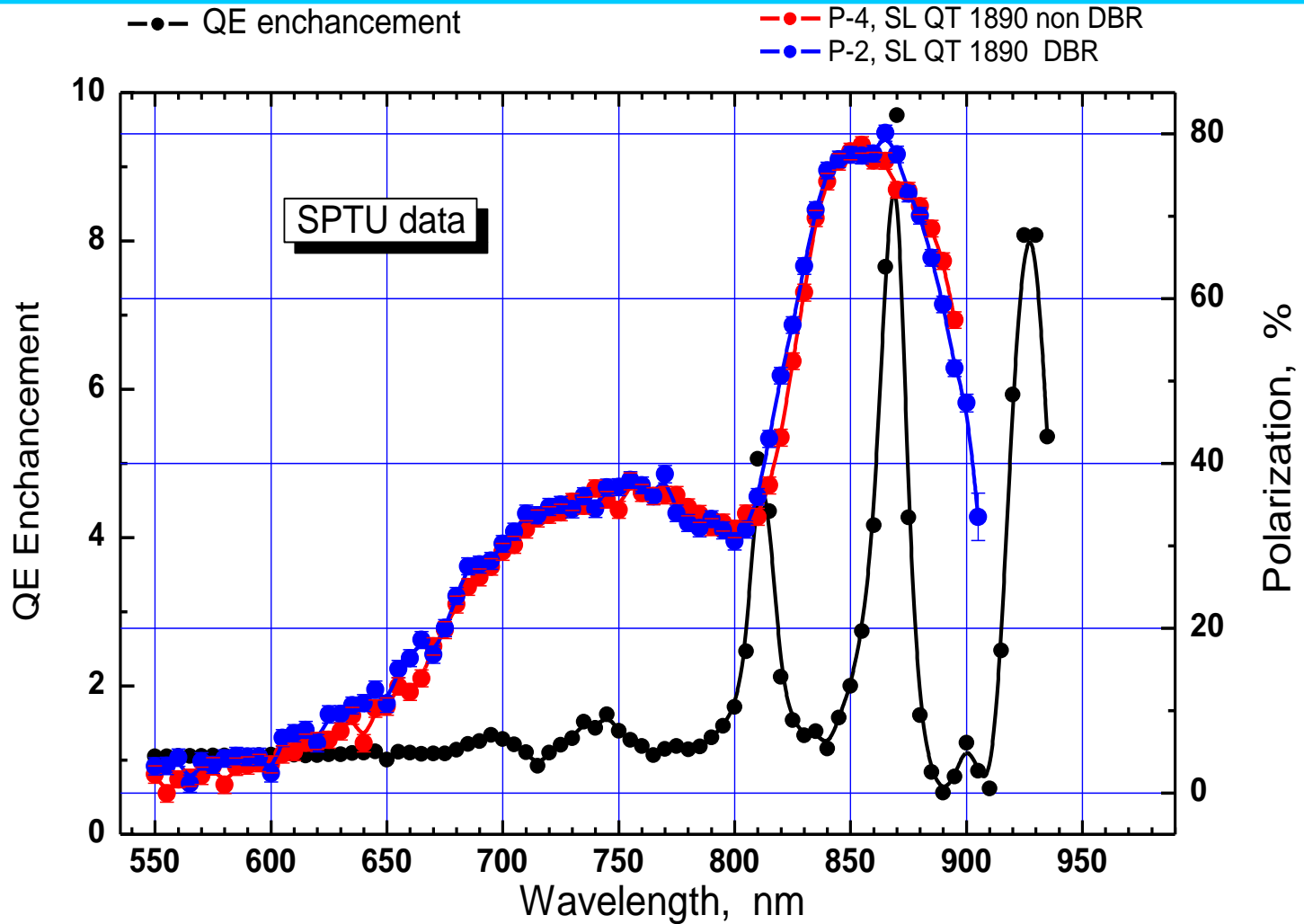
For instance, talk by L. Gerchikov, St. Petersburg, at PESP 2007



Index of refraction of GaAs is such that, 30% of incident light lost at surface. Not sure we can do anything about that.

Add a Distributed Bragg Reflector behind photocathode to reflect back the un-absorbed light...

Resonant enhancement of QE



Accepted for publication at Semiconductors, 2008